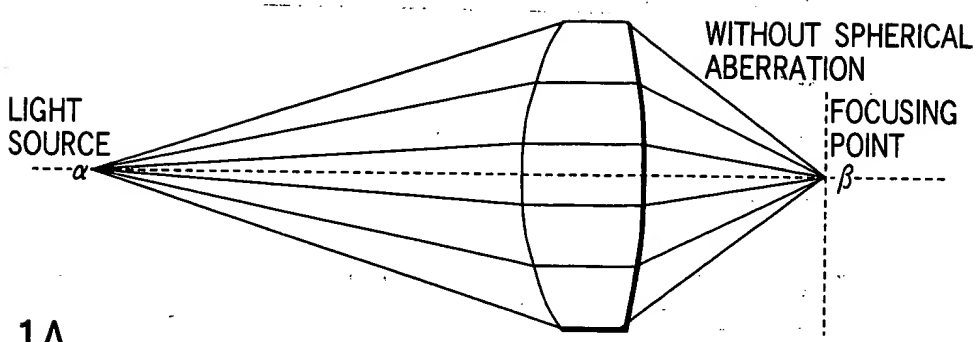

FIG. 1A

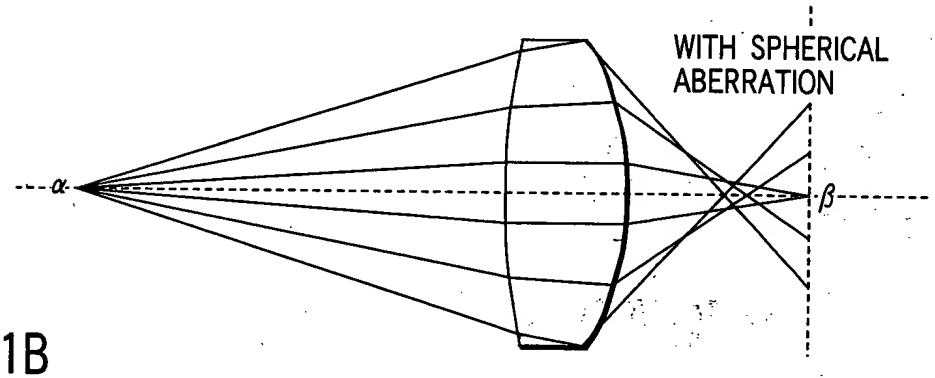

FIG. 1B

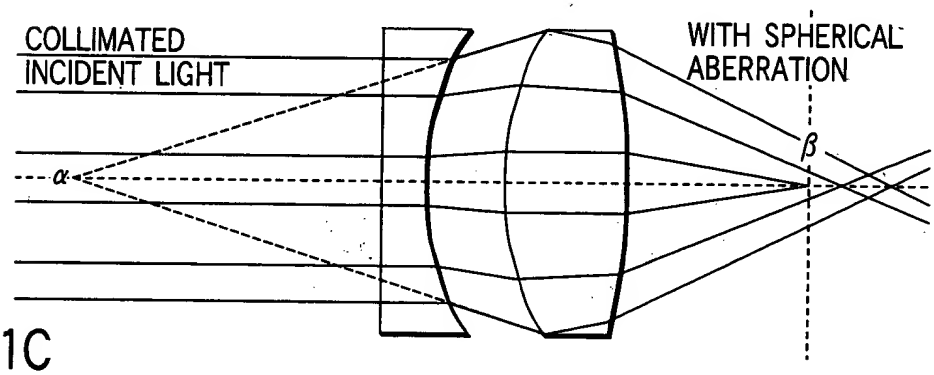

FIG. 1C

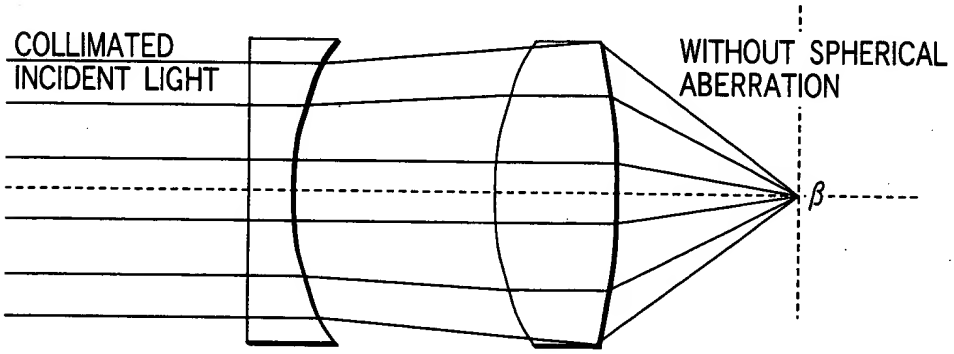

FIG. 1D

STATE WHERE FOCUS IS ATTAINED ON RECORDING LAYER WITH TRANSPARENT LAYER THICKNESS OF REFERENCE VALUE BY USING OPTICAL SYSTEM WITHOUT SPHERICAL ABERRATION
(ASSUMING NO REFRACTIVE INDEX IRREGULARITY)

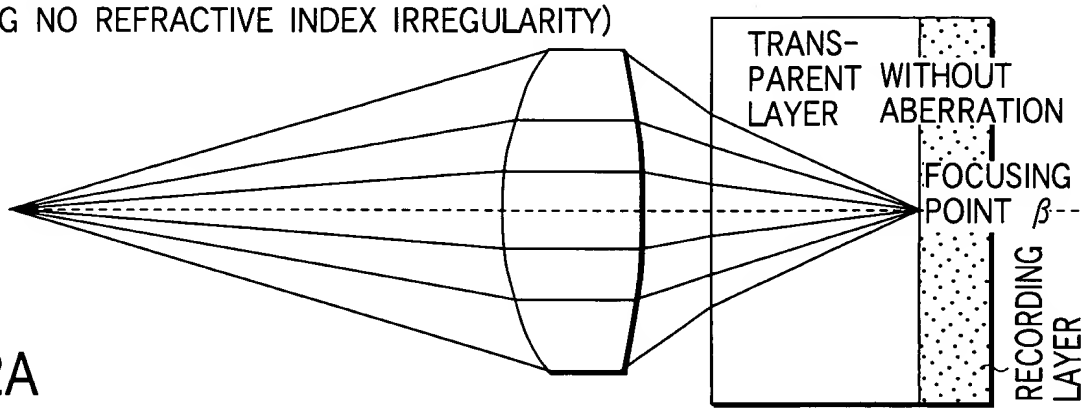

FIG. 2A

STATE WHERE ABERRATION OCCURS WHEN THICKNESS OF TRANSPARENT LAYER VARIES IN DIRECTION IN WHICH IT BECOMES SMALLER THAN REFERENCE VALUE
(THE SAME APPLIES TO CASE WHERE REFRACTIVE INDEX OF TRANSPARENT LAYER VARIES IN DIRECTION IN WHICH IT BECOMES LOWER THAN REFERENCE LEVEL)

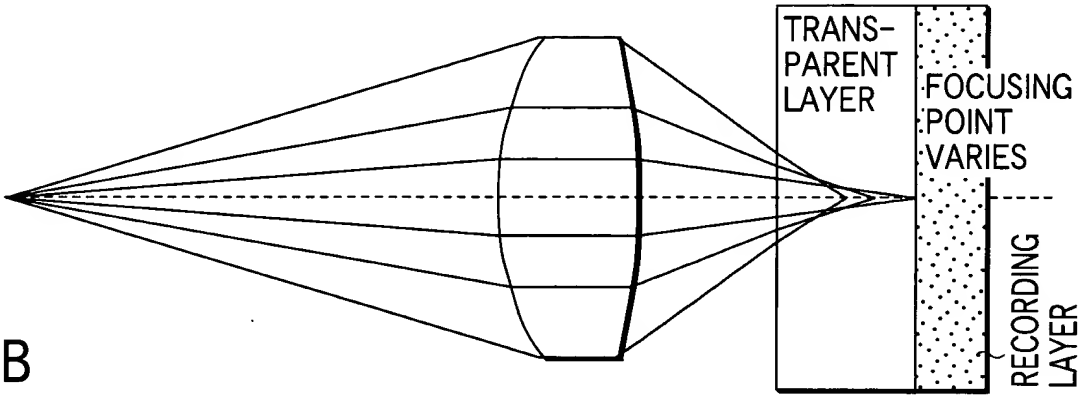

FIG. 2B

STATE WHERE ABERRATION OCCURS WHEN THICKNESS OF TRANSPARENT LAYER VARIES IN DIRECTION IN WHICH IT BECOMES LARGER THAN REFERENCE VALUE
(THE SAME APPLIES TO CASE WHERE REFRACTIVE INDEX OF TRANSPARENT LAYER VARIES IN DIRECTION IN WHICH IT BECOMES HIGHER THAN REFERENCE LEVEL)

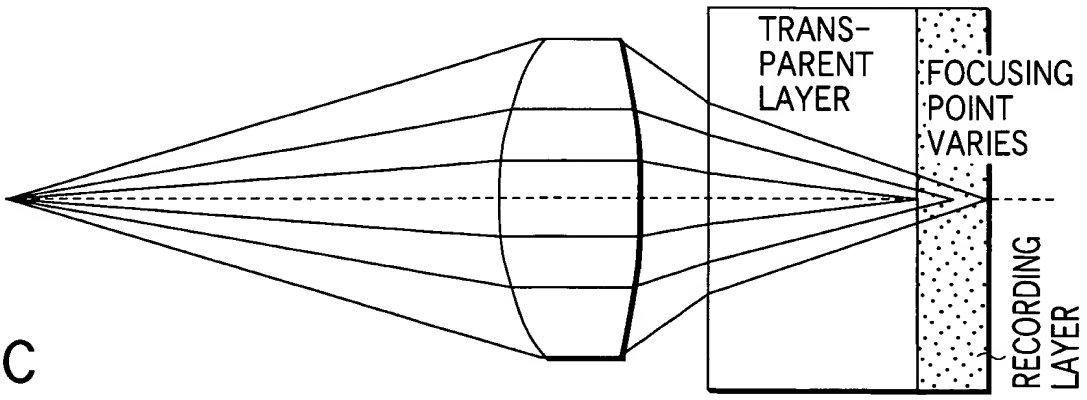

FIG. 2C

STATE WHERE FOCUS IS ADJUSTED WHEN PARALLEL LIGHT IS INCIDENT ON OBJECTIVE LENS WITHOUT ANY THICKNESS IRREGULARITY (REFRACTIVE INDEX IRREGULARITY) OF TRANSPARENT LAYER (ZERO CORRECTION AMOUNT)

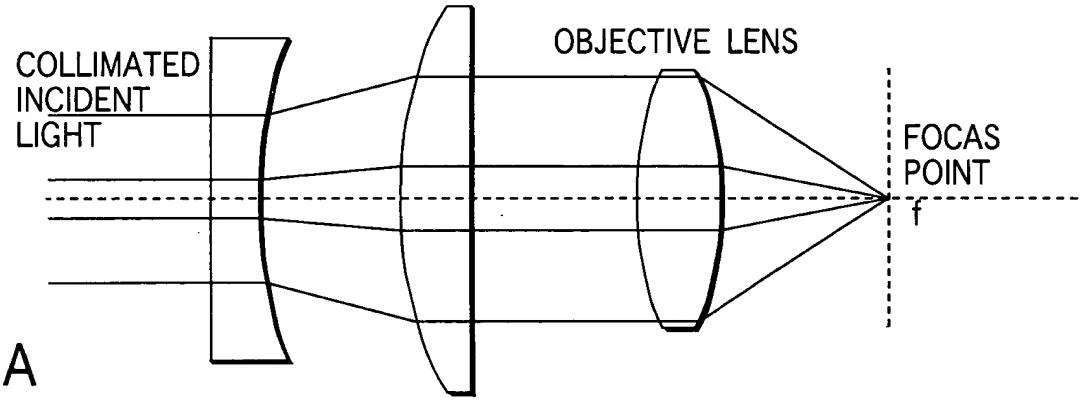

FIG. 3A

STATE WHERE LIGHT INCIDENT ON OBJECTIVE LENS BECOMES NONPARALLEL (CONVERGENT) OWING TO THICKNESS CORRECTION

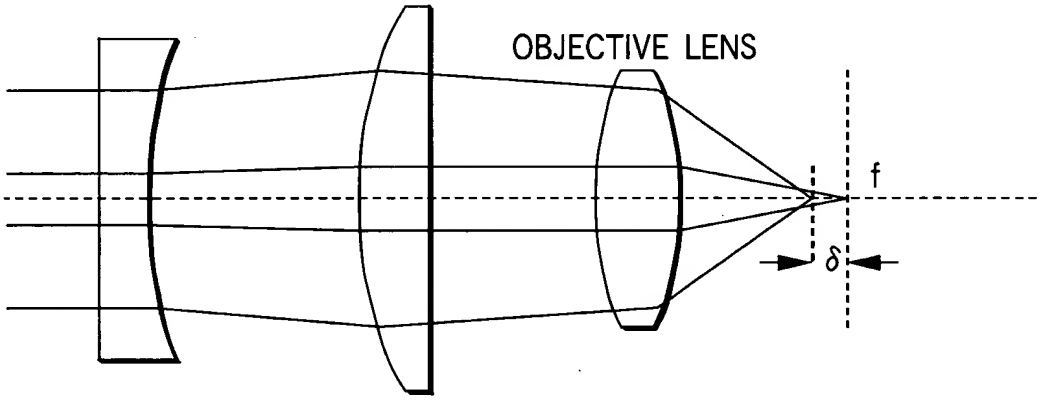

FIG. 3B

STATE WHERE LIGHT INCIDENT ON OBJECTIVE LENS BECOMES NONPARALLEL (DIVERGENT) OWING TO THICKNESS CORRECTION

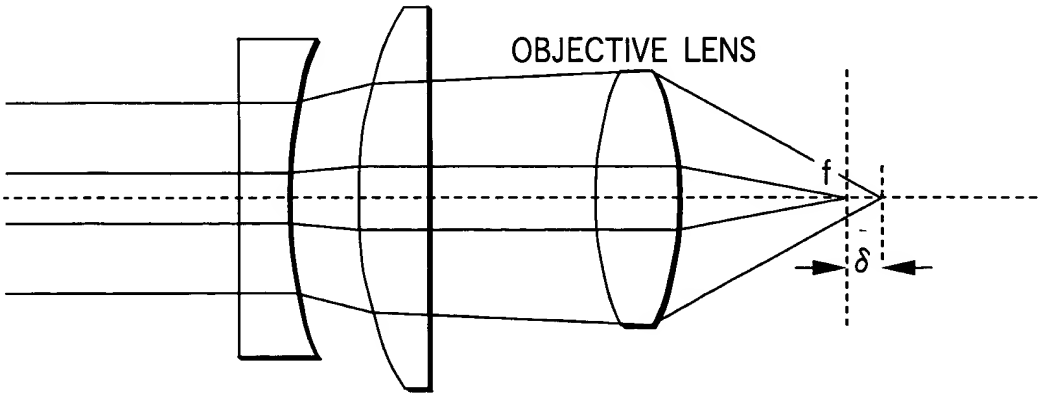

FIG. 3C

IN CASE WHERE FOCUSING POINT β SET BY OBJECTIVE LENS COINCIDES WITH POSITION ON RECORDING LAYER (LIGHT REFLECTED BY RECORDING LAYER AND HAVING PASSED THROUGH OPTICAL SYSTEM UNIT 70 IS KEPT PARALLEL)

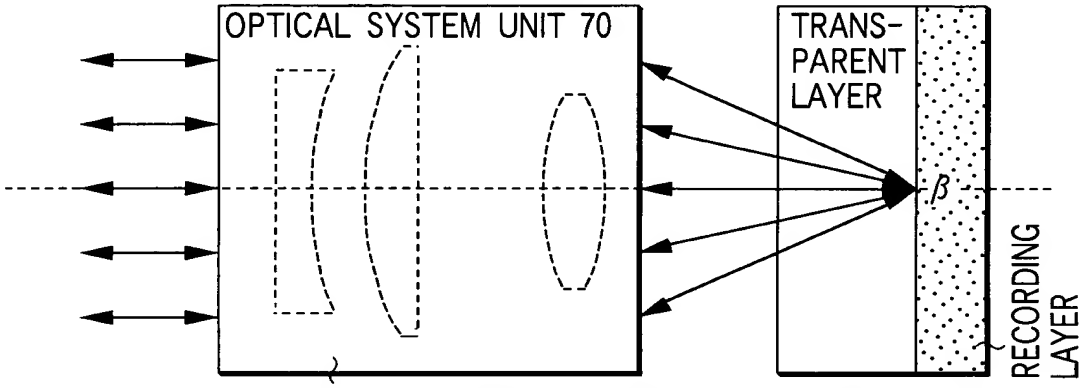

FIG. 4A OBJECTIVE LENS OPTICAL SYSTEM+THICKNESS IRREGULARITY (REFRACTIVE INDEX IRREGULARITY) CORRECTION OPTICAL SYSTEM

IN CASE WHERE FOCUSING POINT β SET BY OBJECTIVE LENS IS LOCATED BEHIND POSITION ON RECORDING LAYER (LIGHT REFLECTED BY RECORDING LAYER AND HAVING PASSED THROUGH OPTICAL SYSTEM UNIT 70 BECOMES DIVERGENT LIGHT)

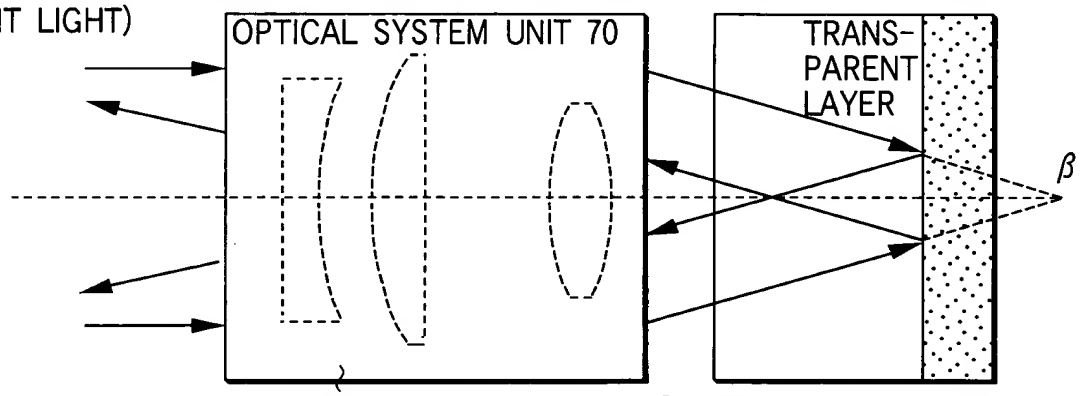

FIG. 4B OBJECTIVE LENS OPTICAL SYSTEM+THICKNESS IRREGULARITY (REFRACTIVE INDEX IRREGULARITY) CORRECTION OPTICAL SYSTEM

IN CASE WHERE FOCUSING POINT β SET BY OBJECTIVE LENS IS LOCATED BEFORE POSITION ON RECORDING LAYER (LIGHT REFLECTED BY RECORDING LAYER AND HAVING PASSED THROUGH OPTICAL SYSTEM UNIT 70 BECOMES CONVERGENT LIGHT)

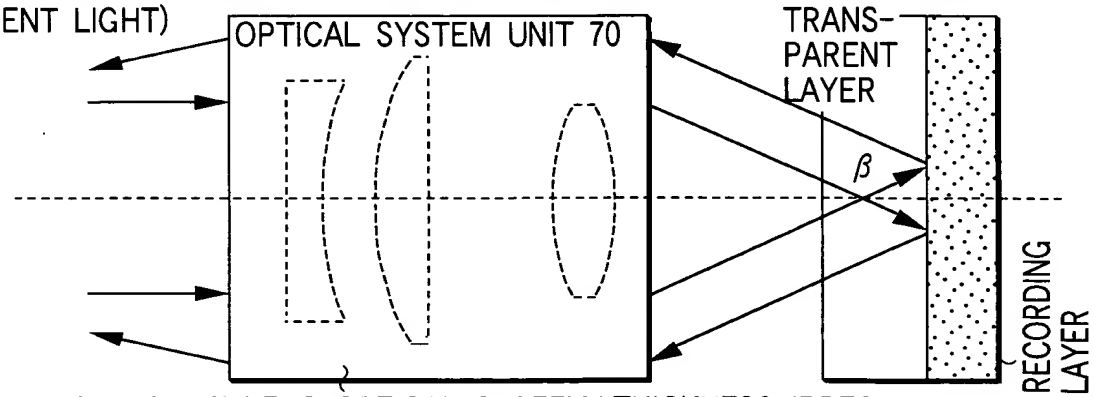

FIG. 4C OBJECTIVE LENS OPTICAL SYSTEM+THICKNESS IRREGULARITY (REFRACTIVE INDEX IRREGULARITY) CORRECTION OPTICAL SYSTEM

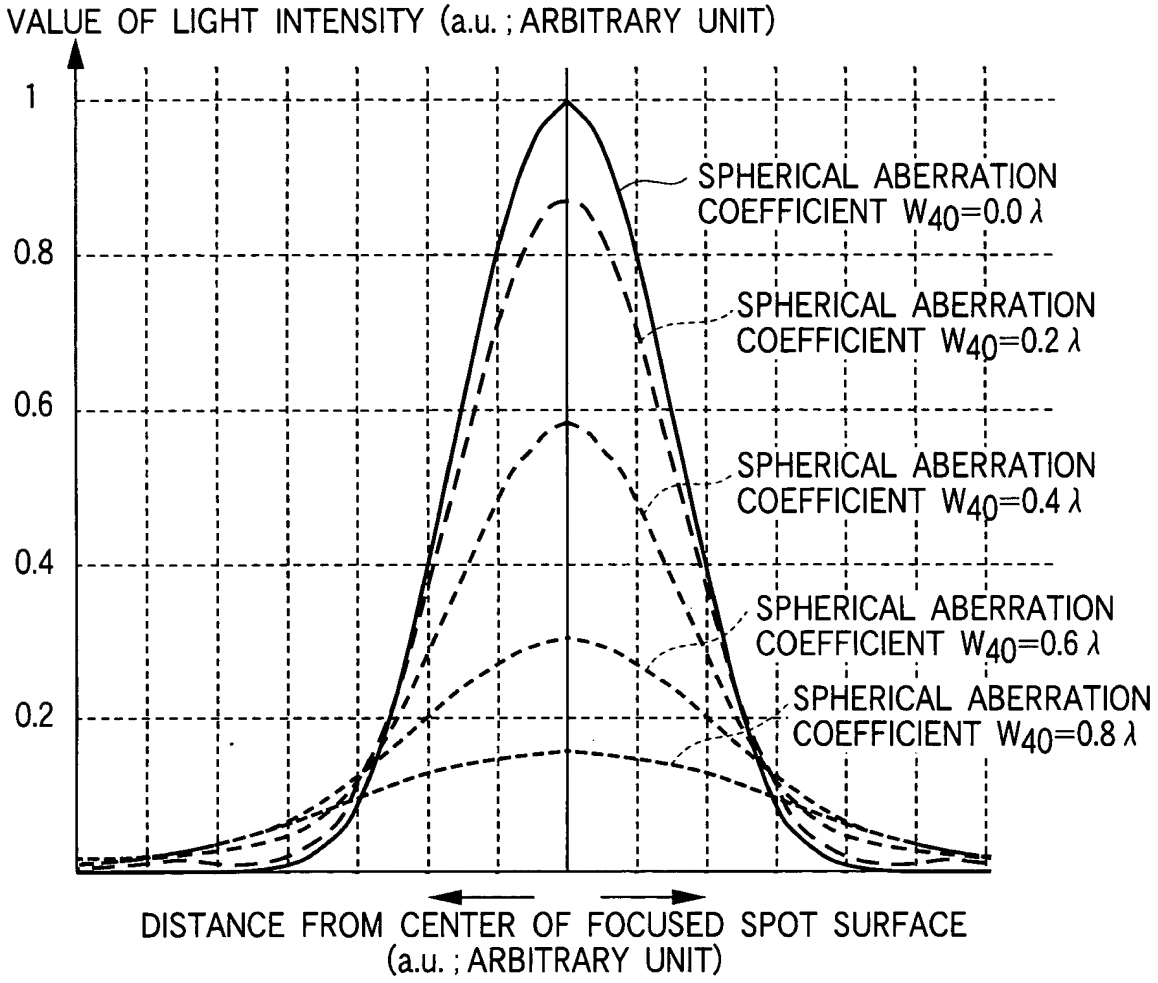
VALUE OF LIGHT INTENSITY (a.u. ; ARBITRARY UNIT)
1
0.8
0.6
0.4
0.2
SPHERICAL ABERRATION COEFFICIENT W40=0.0 λ
SPHERICAL ABERRATION COEFFICIENT W40=0.2 λ
SPHERICAL ABERRATION COEFFICIENT W40=0.4 λ
SPHERICAL ABERRATION COEFFICIENT W40=0.6 λ
SPHERICAL ABERRATION COEFFICIENT W40=0.8 λ
DISTANCE FROM CENTER OF FOCUSED SPOT SURFACE
(a.u. ; ARBITRARY UNIT)

FIG. 5A

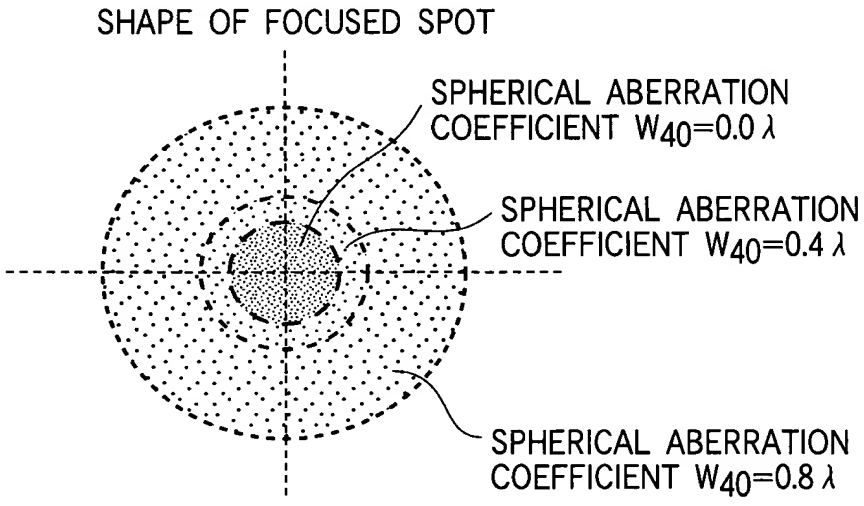
SHAPE OF FOCUSED SPOT
SPHERICAL ABERRATION COEFFICIENT W40=0.0 λ
SPHERICAL ABERRATION COEFFICIENT W40=0.4 λ
SPHERICAL ABERRATION COEFFICIENT W40=0.8 λ

FIG. 5B

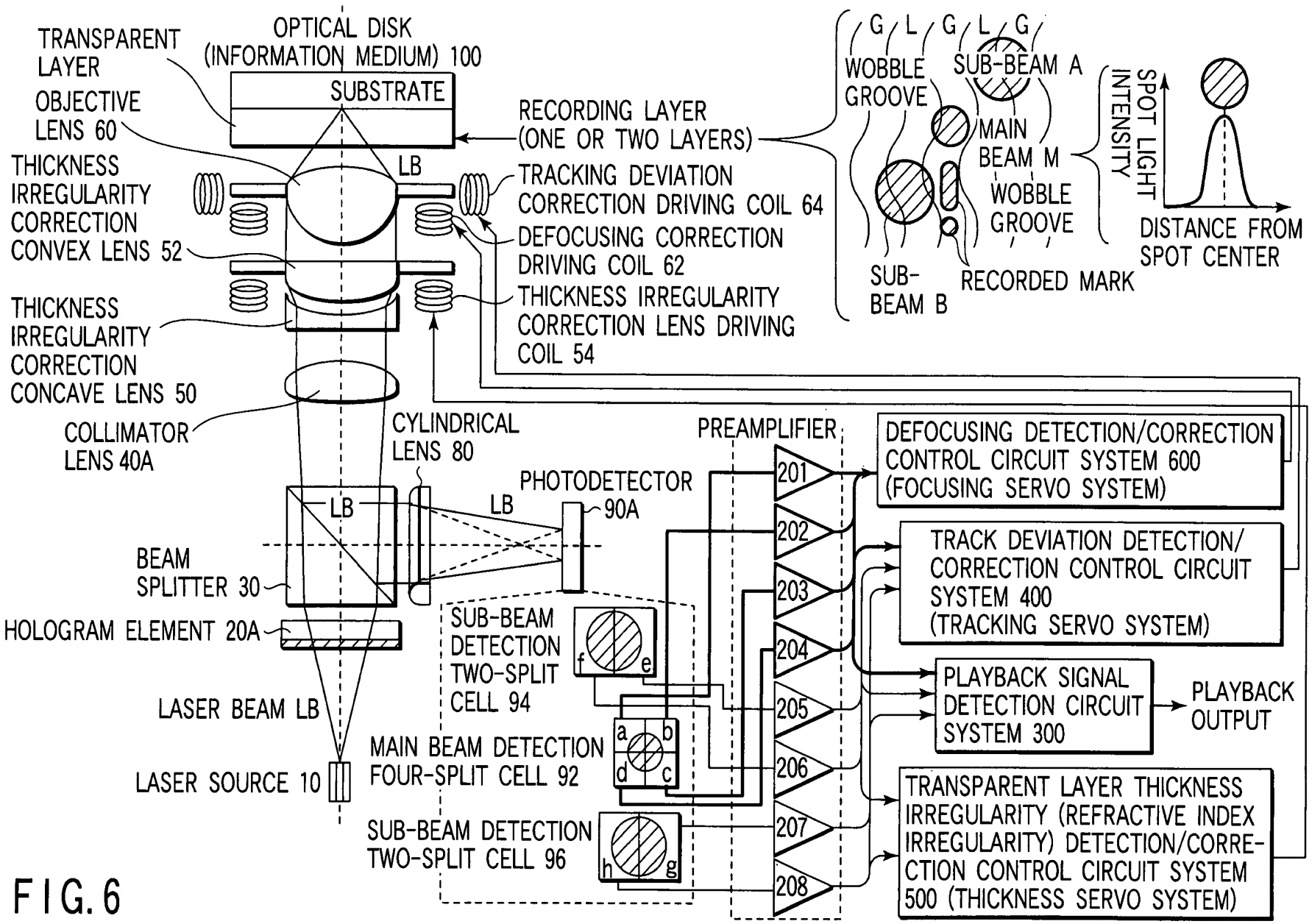

FIG. 6

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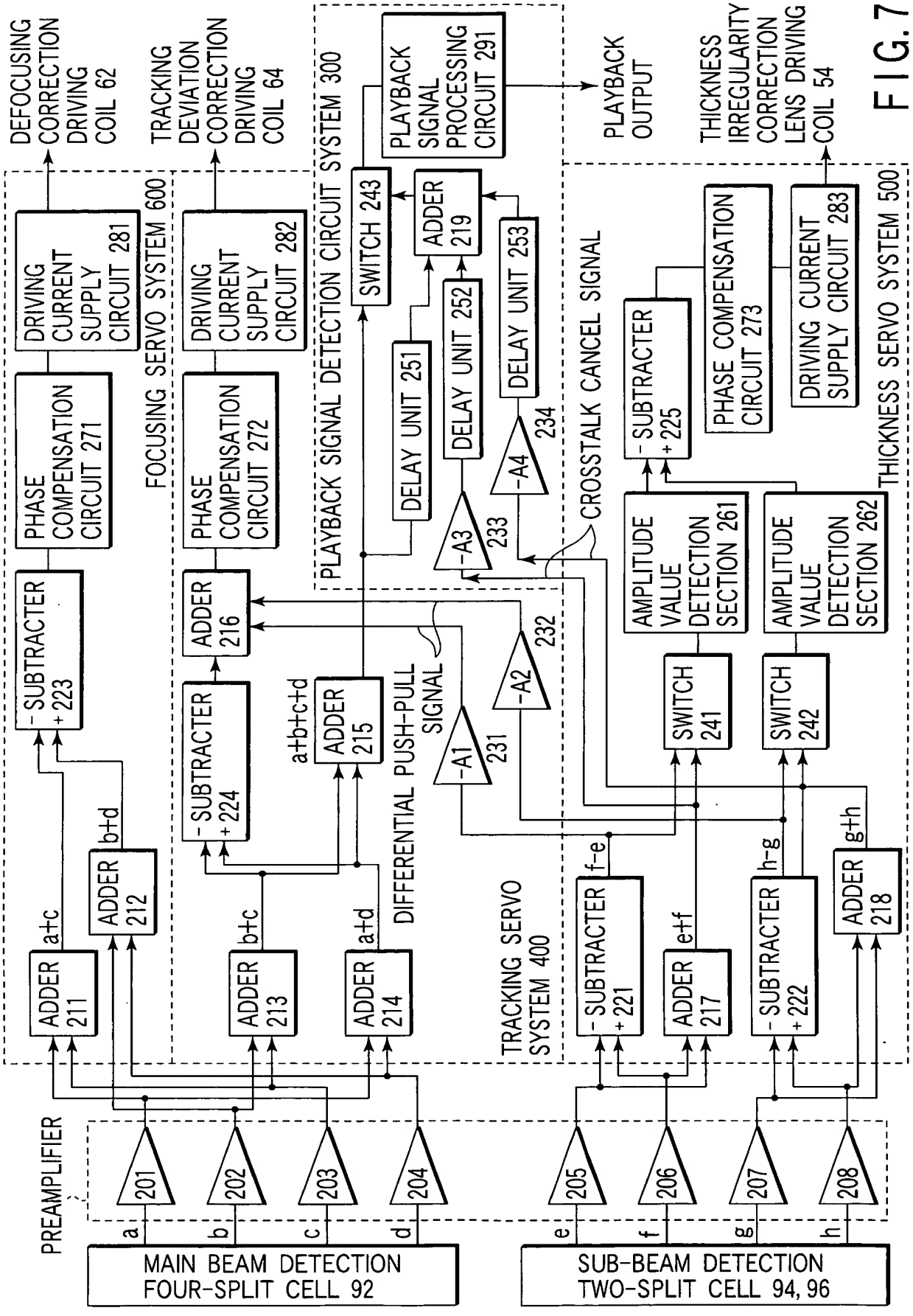
MAIN BEAM DETECTION FOUR-SPLIT CELL 92
SUB-BEAM DETECTION TWO-SPLIT CELL 94, 96
PREAMPLIFIER
201
202
203
204
205
206
207
208
a
b
c
d
e
f
g
h
ADDER 211
ADDER 212
ADDER 213
ADDER 214
ADDER 215
ADDER 216
ADDER 217
ADDER 218
a+c
b+d
b+c
a+d
a+b+c+d
e+f
g+h
- SUBTRACTER + 223
- SUBTRACTER + 224
- SUBTRACTER + 221
- SUBTRACTER + 222
- SUBTRACTER + 225
h-g
f-e
FOCUSING SERVO SYSTEM 600
TRACKING SERVO SYSTEM 400
THICKNESS SERVO SYSTEM 500
PHASE COMPENSATION CIRCUIT 271
PHASE COMPENSATION CIRCUIT 272
PHASE COMPENSATION CIRCUIT 273
DRIVING CURRENT SUPPLY CIRCUIT 281
DRIVING CURRENT SUPPLY CIRCUIT 282
DRIVING CURRENT SUPPLY CIRCUIT 283
DEFOCUSING CORRECTION DRIVING COIL 62
TRACKING DEVIATION CORRECTION DRIVING COIL 64
THICKNESS IRREGULARITY CORRECTION LENS DRIVING COIL 54
PLAYBACK SIGNAL DETECTION CIRCUIT SYSTEM 300
PLAYBACK SIGNAL PROCESSING CIRCUIT 291
PLAYBACK OUTPUT
SWITCH 241
SWITCH 242
SWITCH 243
AMPLITUDE VALUE DETECTION SECTION 261
AMPLITUDE VALUE DETECTION SECTION 262
DELAY UNIT 251
DELAY UNIT 252
DELAY UNIT 253
-A1 231
-A2 232
-A3 233
-A4 234
DIFFERENTIAL PUSH-PULL SIGNAL
CROSSTALK CANCEL SIGNAL

FIG. 7

SPOT SIZE OF SUB-BEAM A DECREASES, AND SPOT SIZE OF SUB-BEAM B INCREASES DUE TO THICKNESS IRREGULARITY

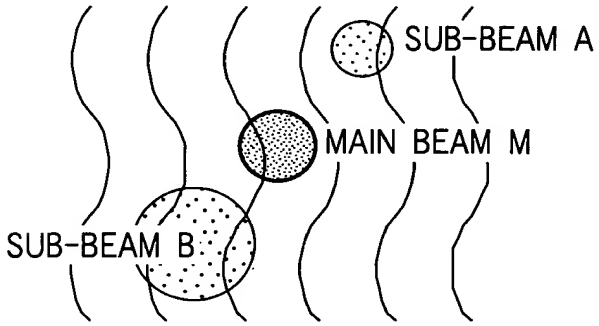

FIG. 8A

ABERRATION OF SUB-BEAM A=ABERRATION OF SUB-BEAM B
(ABERRATION OF MAIN BEAM M IS ZERO OR MINIMUM)

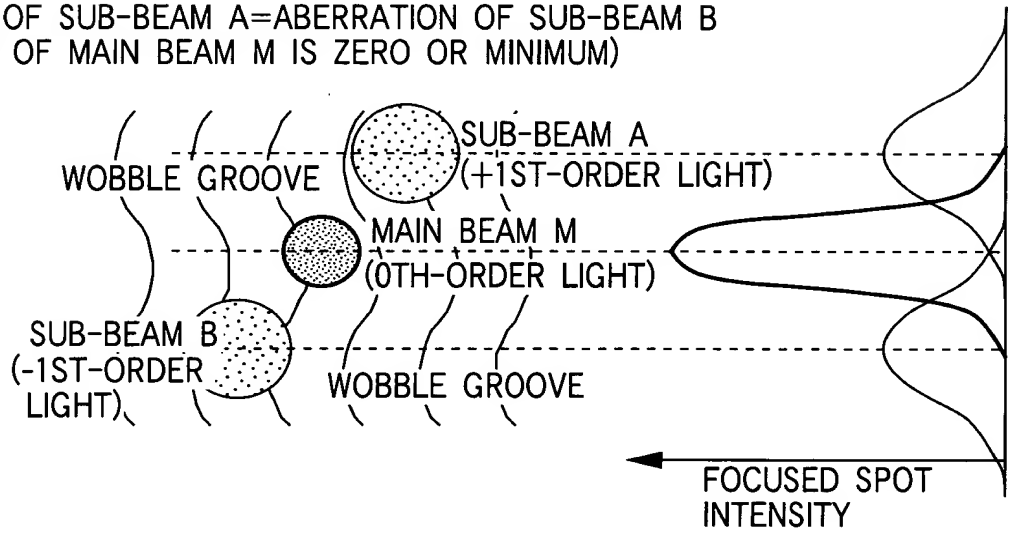

FIG. 8B

SPOT SIZE OF SUB-BEAM A INCREASES, AND SPOT SIZE OF SUB-BEAM B DECREASES DUE TO THICKNESS IRREGULARITY

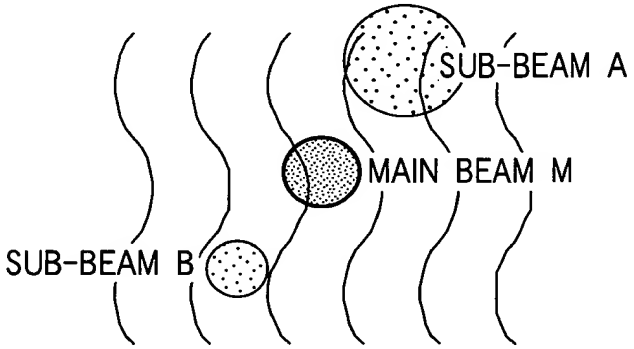

FIG. 8C

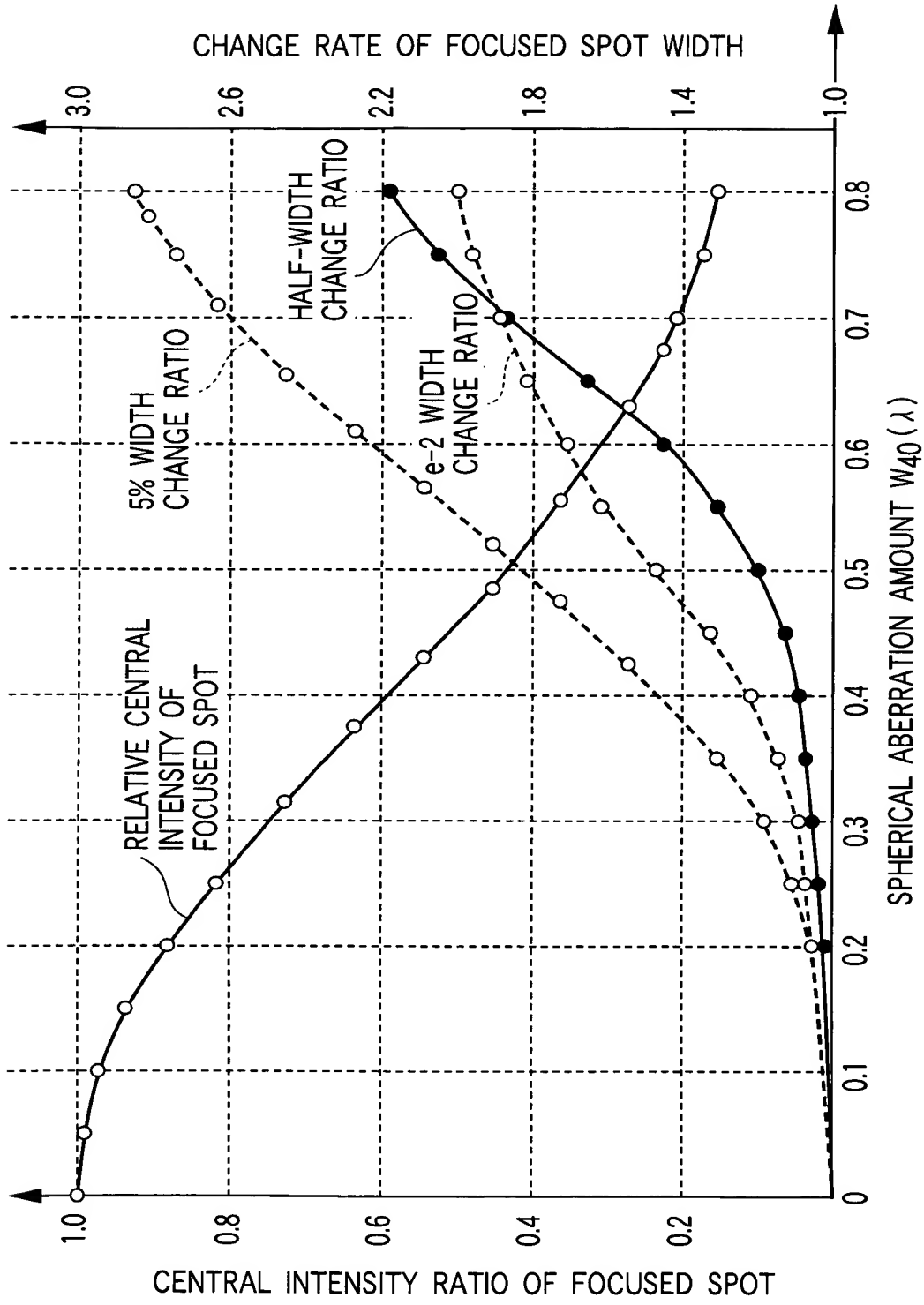
CHANGE RATE OF FOCUSED SPOT WIDTH
3.0
2.6
2.2
1.8
1.4
1.0
HALF-WIDTH CHANGE RATIO
5% WIDTH CHANGE RATIO
e-2 WIDTH CHANGE RATIO
RELATIVE CENTRAL INTENSITY OF FOCUSED SPOT
0.8
0.7
0.6
0.5
0.4
0.3
0.2
0.1
0
SPHERICAL ABERRATION AMOUNT W40(λ)
1.0
0.8
0.6
0.4
0.2
CENTRAL INTENSITY RATIO OF FOCUSED SPOT

FIG. 9

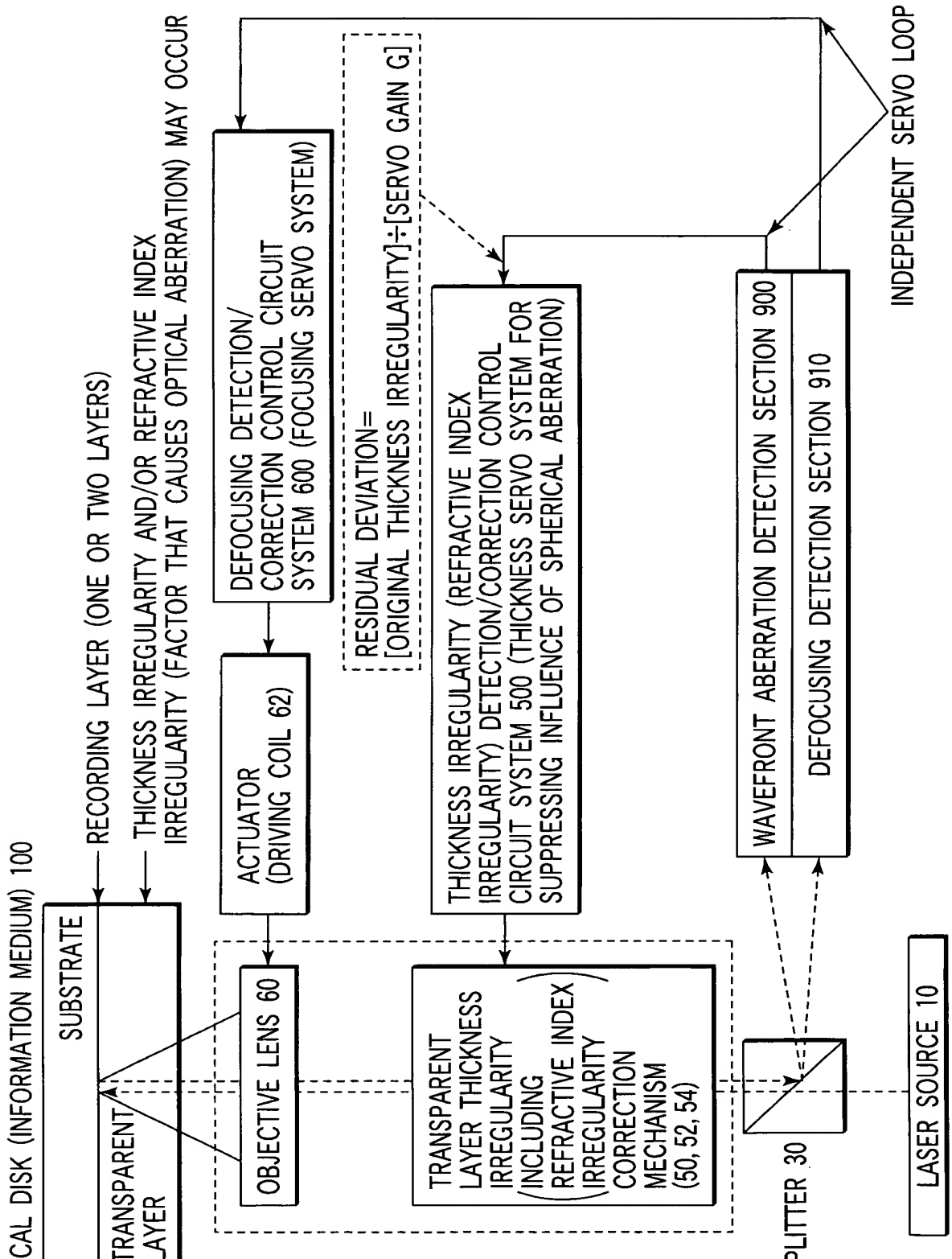
OPTICAL DISK (INFORMATION MEDIUM) 100
SUBSTRATE
TRANSPARENT LAYER
RECORDING LAYER (ONE OR TWO LAYERS)
THICKNESS IRREGULARITY AND/OR REFRACTIVE INDEX IRREGULARITY (FACTOR THAT CAUSES OPTICAL ABERRATION) MAY OCCUR
OBJECTIVE LENS 60
ACTUATOR (DRIVING COIL 62)
DEFOCUSING DETECTION/ CORRECTION CONTROL CIRCUIT SYSTEM 600 (FOCUSING SERVO SYSTEM)
RESIDUAL DEVIATION= [ORIGINAL THICKNESS IRREGULARITY]÷[SERVO GAIN G]
THICKNESS IRREGULARITY (REFRACTIVE INDEX IRREGULARITY) DETECTION/CORRECTION CONTROL CIRCUIT SYSTEM 500 (THICKNESS SERVO SYSTEM FOR SUPPRESSING INFLUENCE OF SPHERICAL ABERRATION)
TRANSPARENT LAYER THICKNESS IRREGULARITY (INCLUDING REFRACTIVE INDEX IRREGULARITY) CORRECTION MECHANISM (50, 52, 54)
WAVEFRONT ABERRATION DETECTION SECTION 900
DEFOCUSING DETECTION SECTION 910
INDEPENDENT SERVO LOOP
BEAM SPLITTER 30
LASER SOURCE 10

FIG. 10

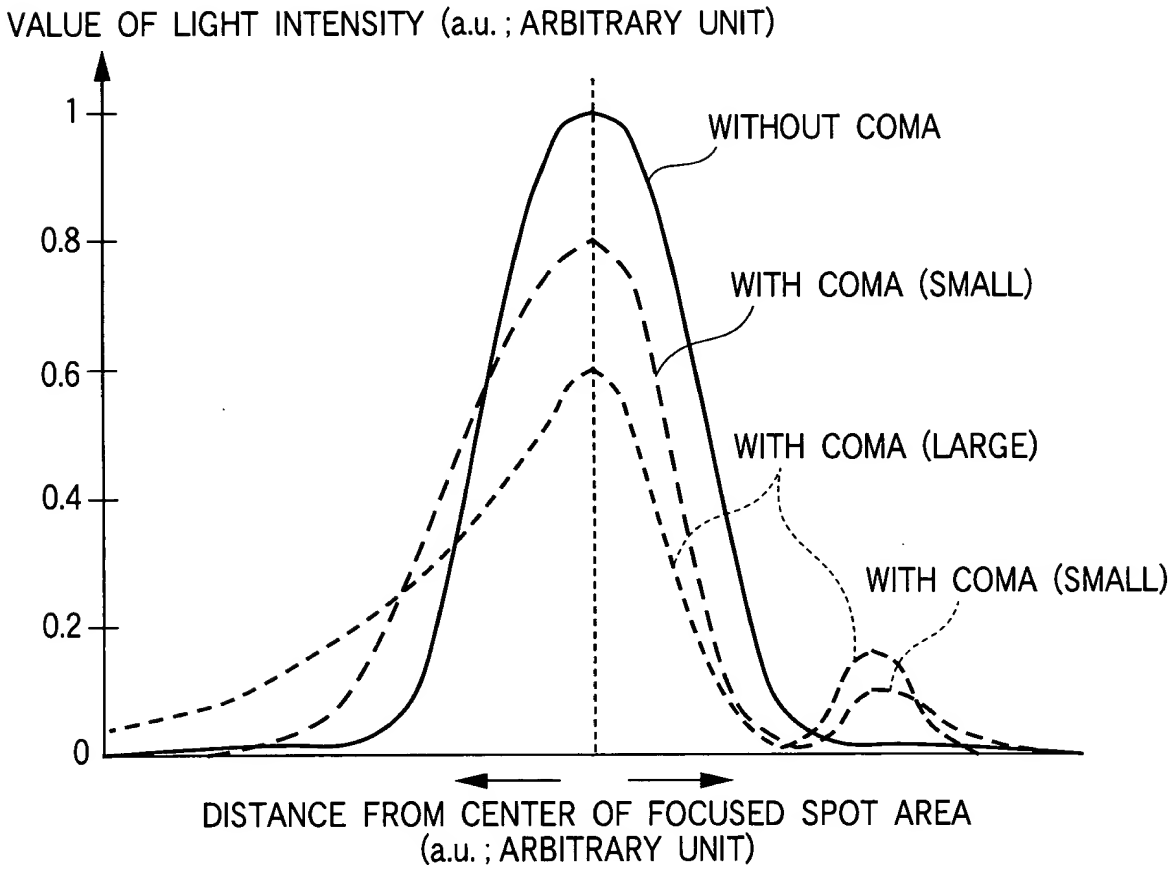

FIG. 11A

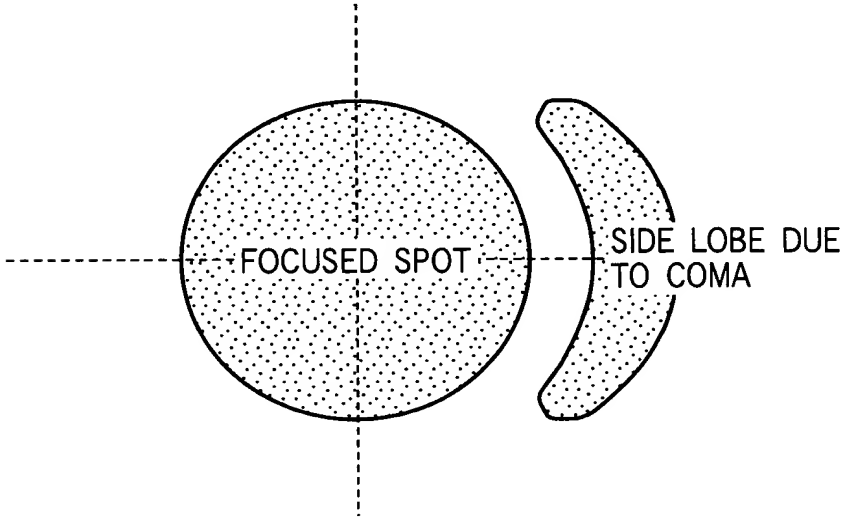

FIG. 11B

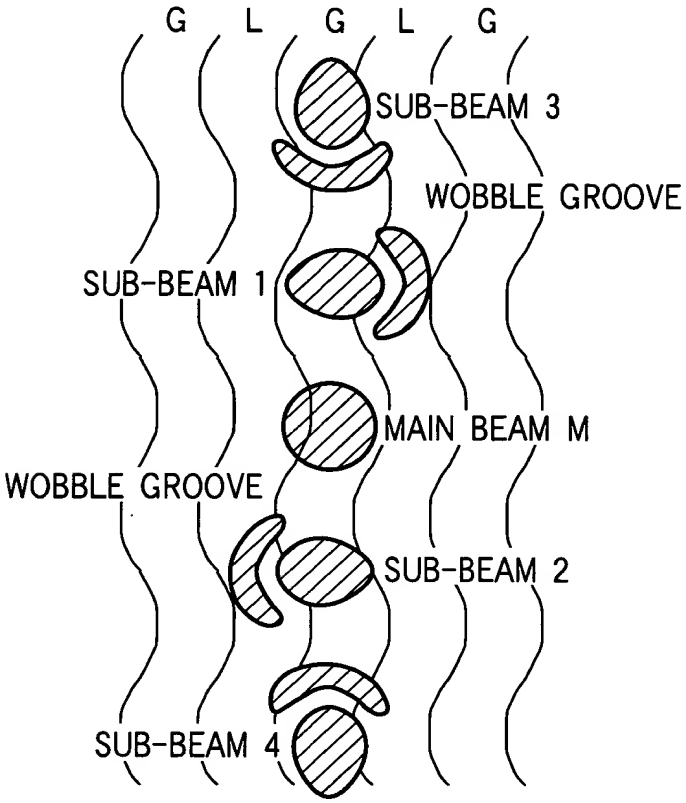

FIG. 12A

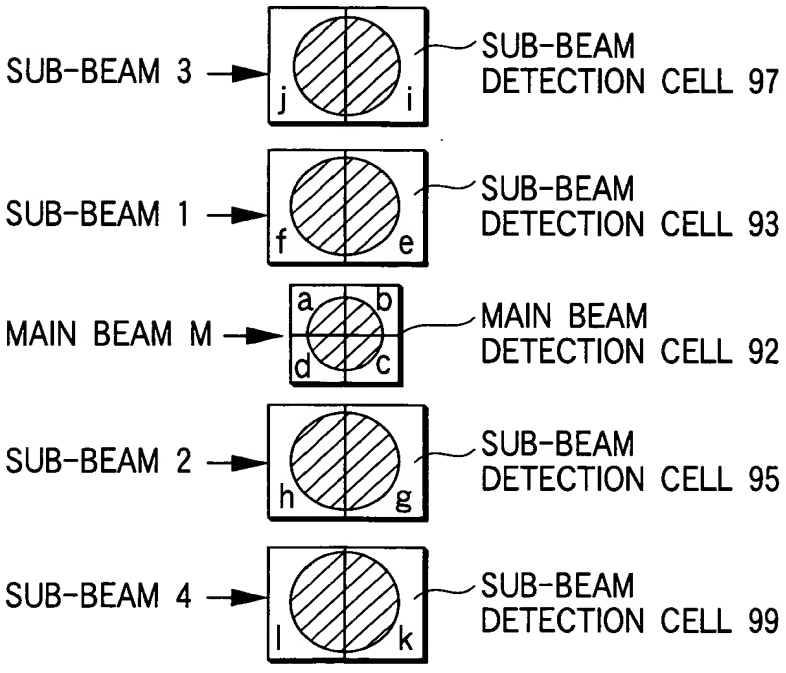

FIG. 12B

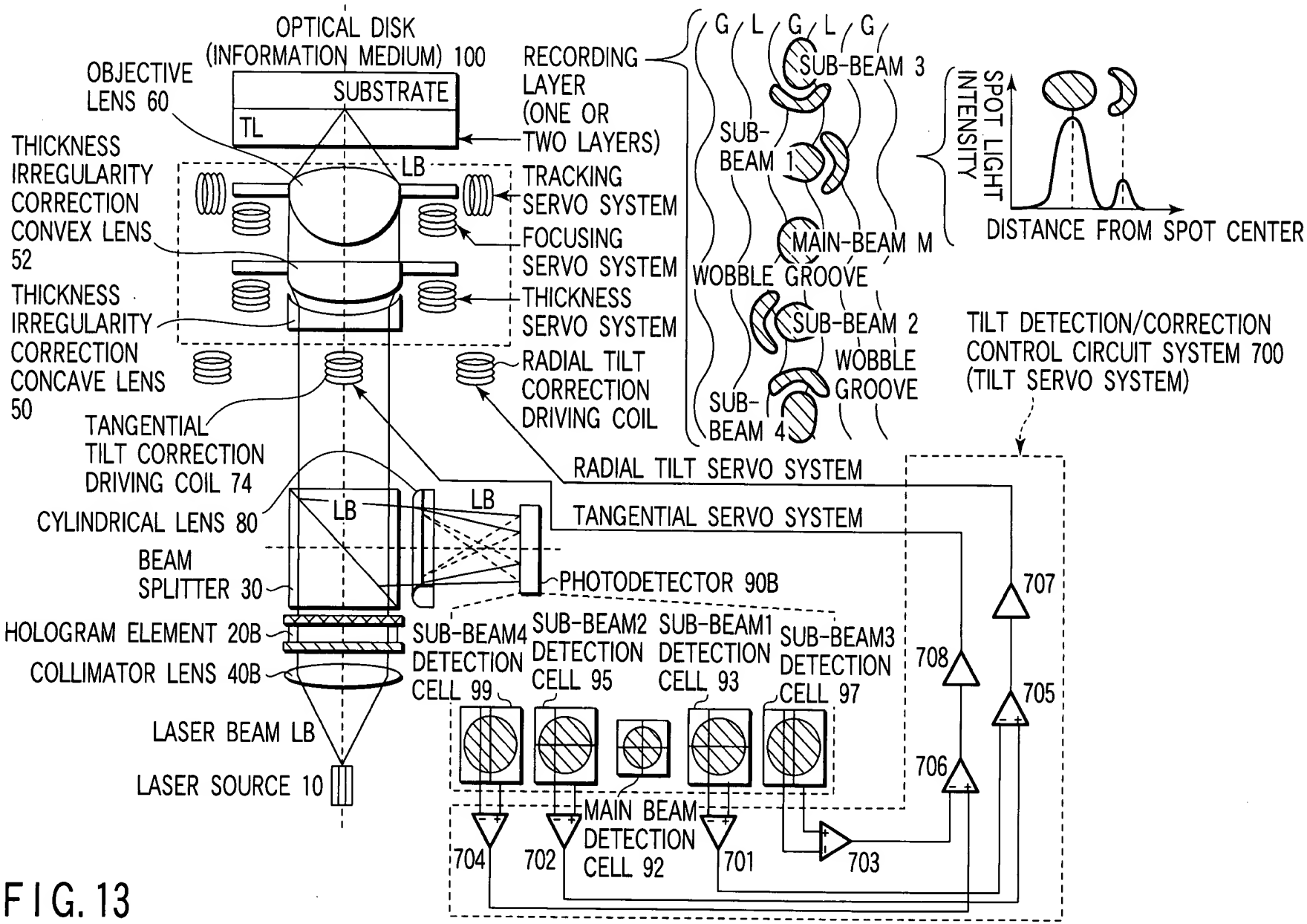

FIG. 13

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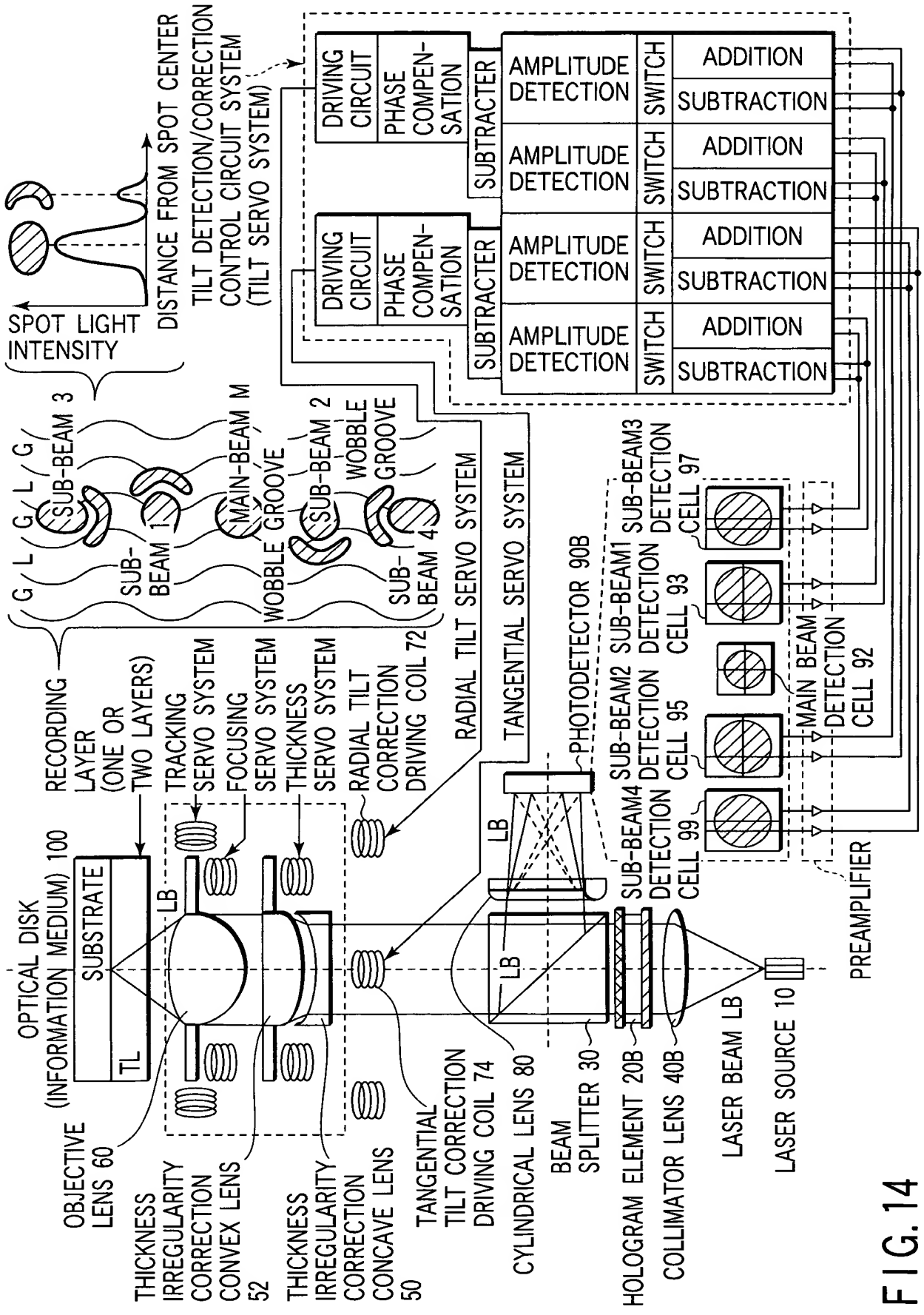
OPTICAL DISK (INFORMATION MEDIUM) 100
SUBSTRATE
TL
RECORDING LAYER (ONE OR TWO LAYERS)
OBJECTIVE LENS 60
LB
TRACKING SERVO SYSTEM
FOCUSING SERVO SYSTEM
THICKNESS SERVO SYSTEM
RADIAL TILT CORRECTION DRIVING COIL 72
RADIAL TILT SERVO SYSTEM
TANGENTIAL SERVO SYSTEM
THICKNESS IRREGULARITY CORRECTION CONVEX LENS 52
THICKNESS IRREGULARITY CORRECTION CONCAVE LENS 50
TANGENTIAL TILT CORRECTION DRIVING COIL 74
CYLINDRICAL LENS 80
BEAM SPLITTER 30
PHOTODETECTOR 90B
HOLOGRAM ELEMENT 20B
COLLIMATOR LENS 40B
LASER BEAM LB
LASER SOURCE 10
SUB-BEAM4 DETECTION CELL 99
SUB-BEAM2 DETECTION CELL 95
SUB-BEAM1 DETECTION CELL 93
SUB-BEAM3 DETECTION CELL 97
MAIN BEAM DETECTION CELL 92
PREAMPLIFIER
G L G L G
SUB-BEAM 3
SUB-BEAM 1
MAIN-BEAM M
WOBBLE GROOVE
SUB-BEAM 2
SUB-BEAM 4
SPOT LIGHT INTENSITY
DISTANCE FROM SPOT CENTER
TILT DETECTION/CORRECTION CONTROL CIRCUIT SYSTEM (TILT SERVO SYSTEM)
DRIVING CIRCUIT
PHASE COMPEN-SATION
SUBTRACTER
AMPLITUDE DETECTION
SWITCH
ADDITION
SUBTRACTION

FIG. 14

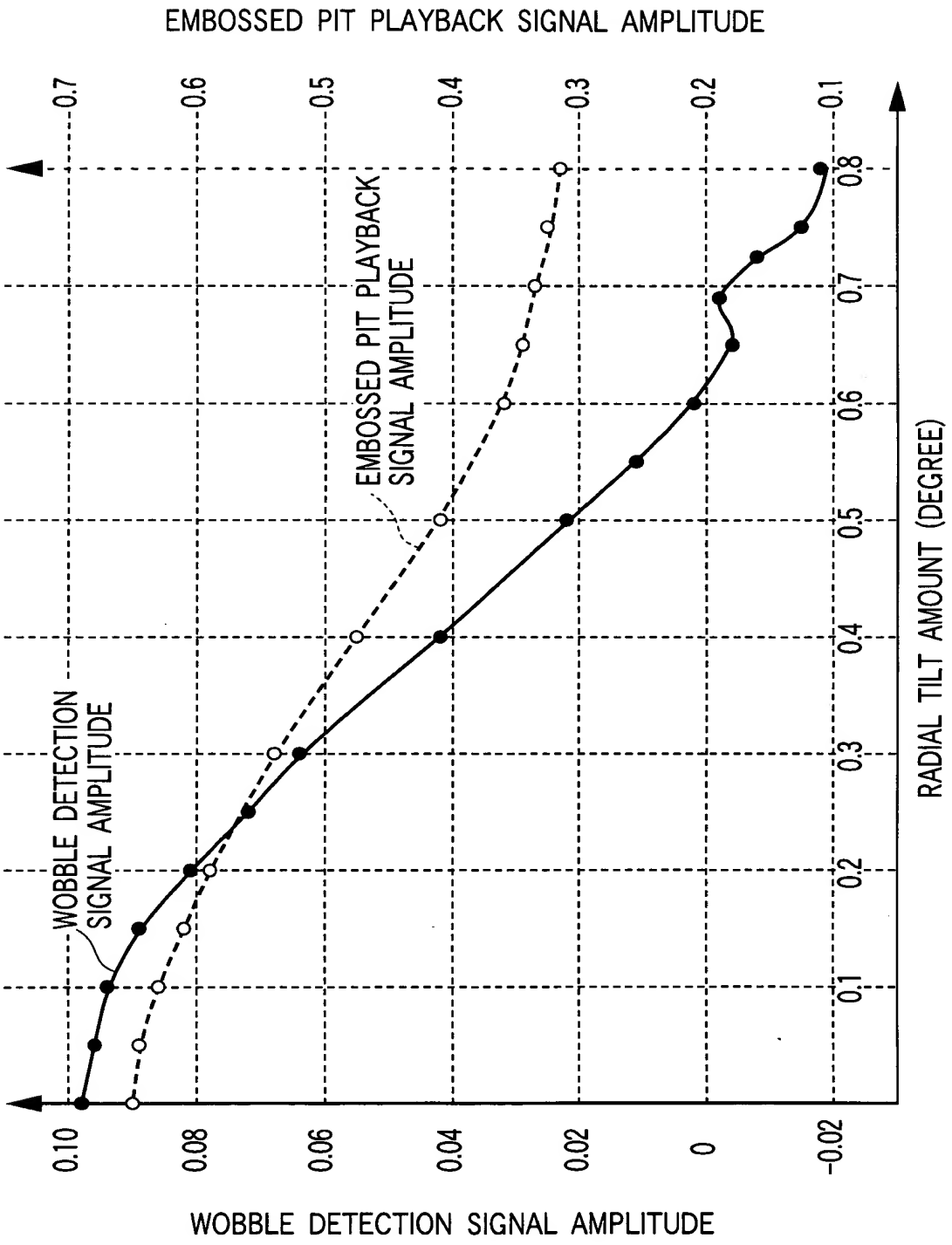
EMBOSSED PIT PLAYBACK SIGNAL AMPLITUDE
0.7
0.6
0.5
0.4
0.3
0.2
0.1
EMBOSSED PIT PLAYBACK SIGNAL AMPLITUDE
WOBBLE DETECTION SIGNAL AMPLITUDE
0.8
0.7
0.6
0.5
0.4
0.3
0.2
0.1
RADIAL TILT AMOUNT (DEGREE)
0.10
0.08
0.06
0.04
0.02
0
-0.02
WOBBLE DETECTION SIGNAL AMPLITUDE

FIG. 15

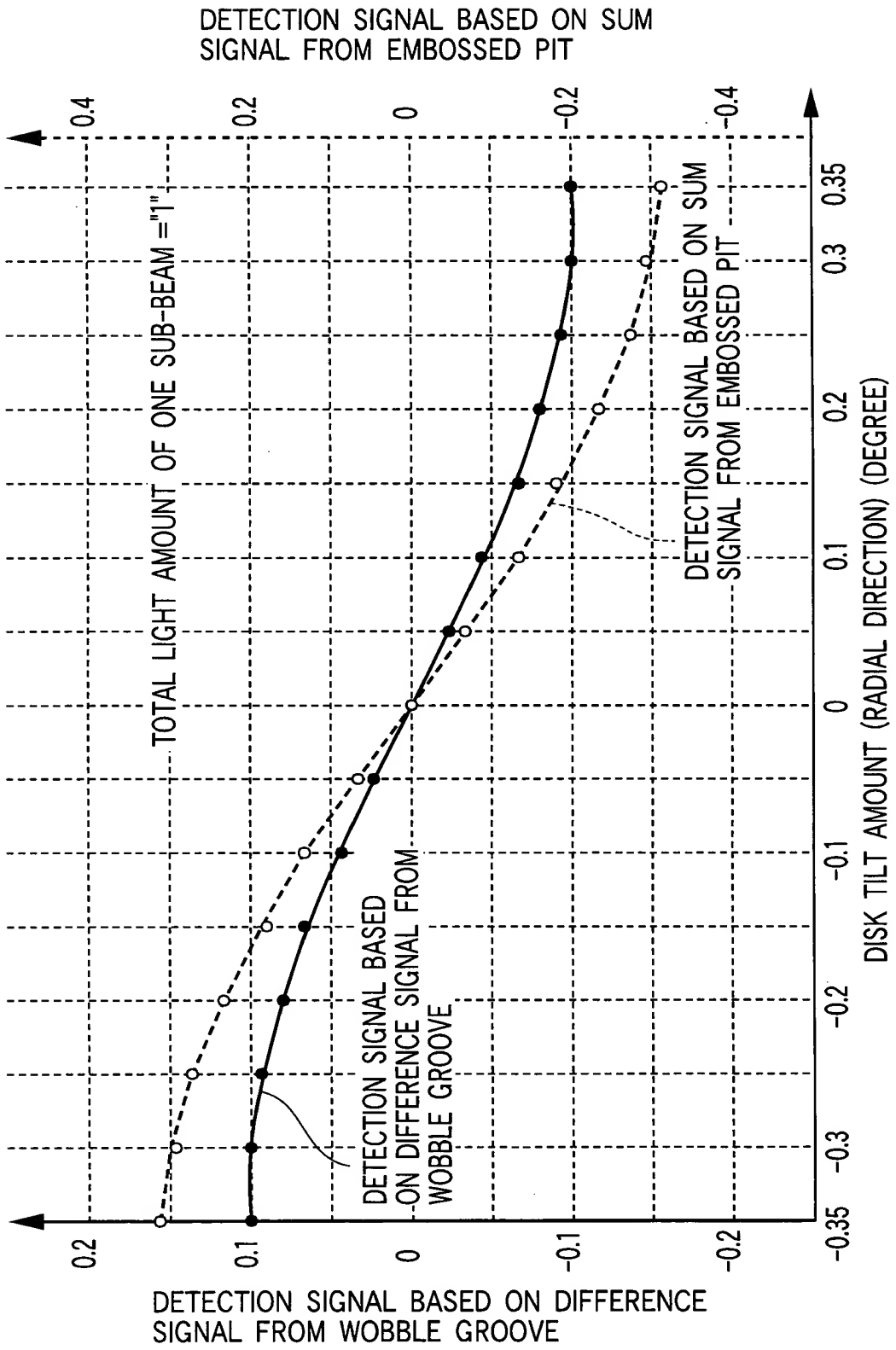
DETECTION SIGNAL BASED ON SUM SIGNAL FROM EMBOSSED PIT
TOTAL LIGHT AMOUNT OF ONE SUB-BEAM ="1"
0.4
0.2
0
-0.2
-0.4
DETECTION SIGNAL BASED ON SUM SIGNAL FROM EMBOSSED PIT
DISK TILT AMOUNT (RADIAL DIRECTION) (DEGREE)
0.35
0.3
0.2
0.1
0
-0.1
-0.2
-0.3
-0.35
DETECTION SIGNAL BASED ON DIFFERENCE SIGNAL FROM WOBBLE GROOVE
0.2
0.1
0
-0.1
-0.2
DETECTION SIGNAL BASED ON DIFFERENCE SIGNAL FROM WOBBLE GROOVE

FIG. 16

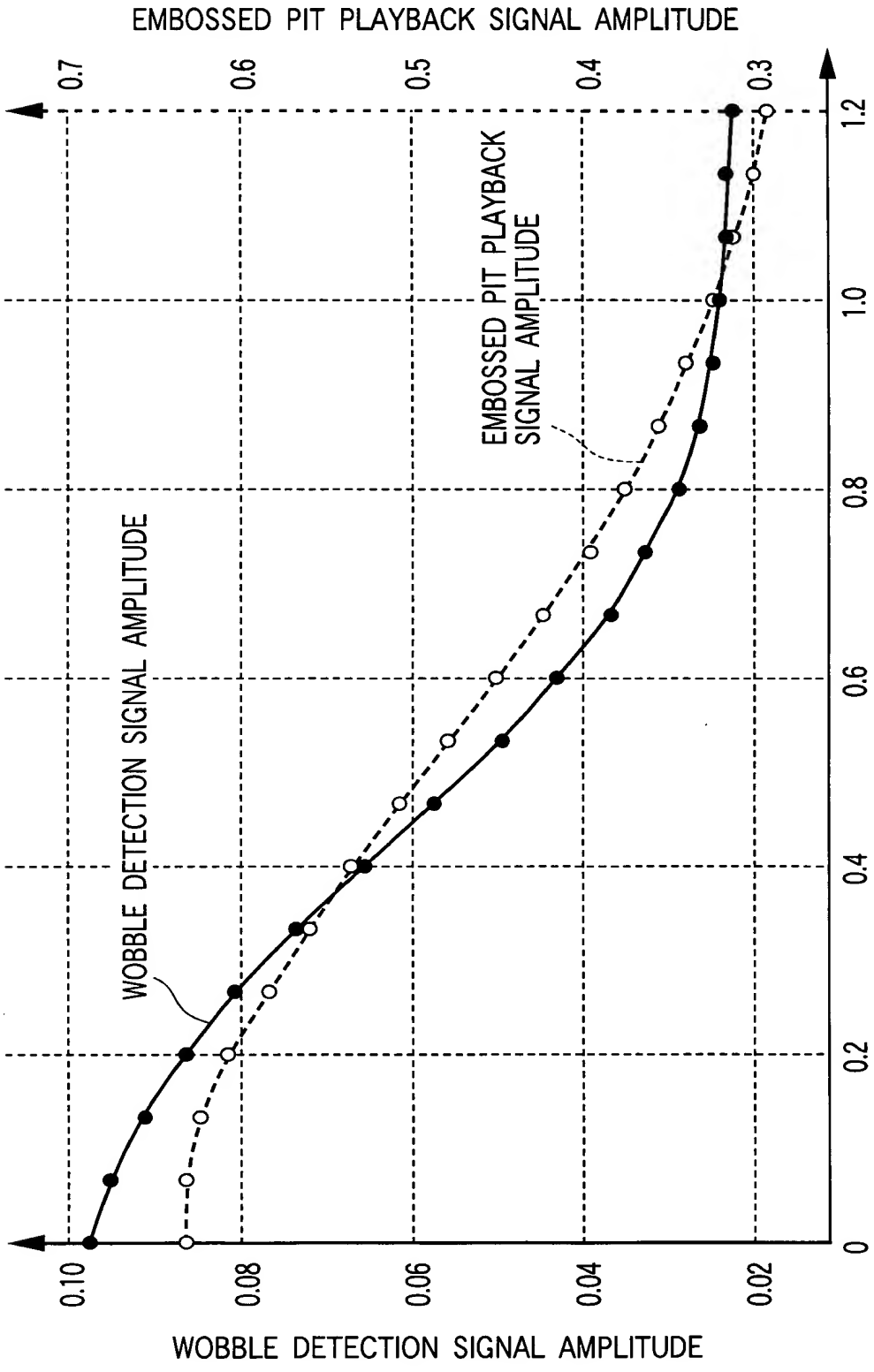
EMBOSSED PIT PLAYBACK SIGNAL AMPLITUDE
0.7
0.6
0.5
0.4
0.3
EMBOSSED PIT PLAYBACK SIGNAL AMPLITUDE
WOBBLE DETECTION SIGNAL AMPLITUDE
1.2
1.0
0.8
0.6
0.4
0.2
0
TANGENTIAL TILT AMOUNT (DEGREE)
0.10
0.08
0.06
0.04
0.02
WOBBLE DETECTION SIGNAL AMPLITUDE

FIG. 17

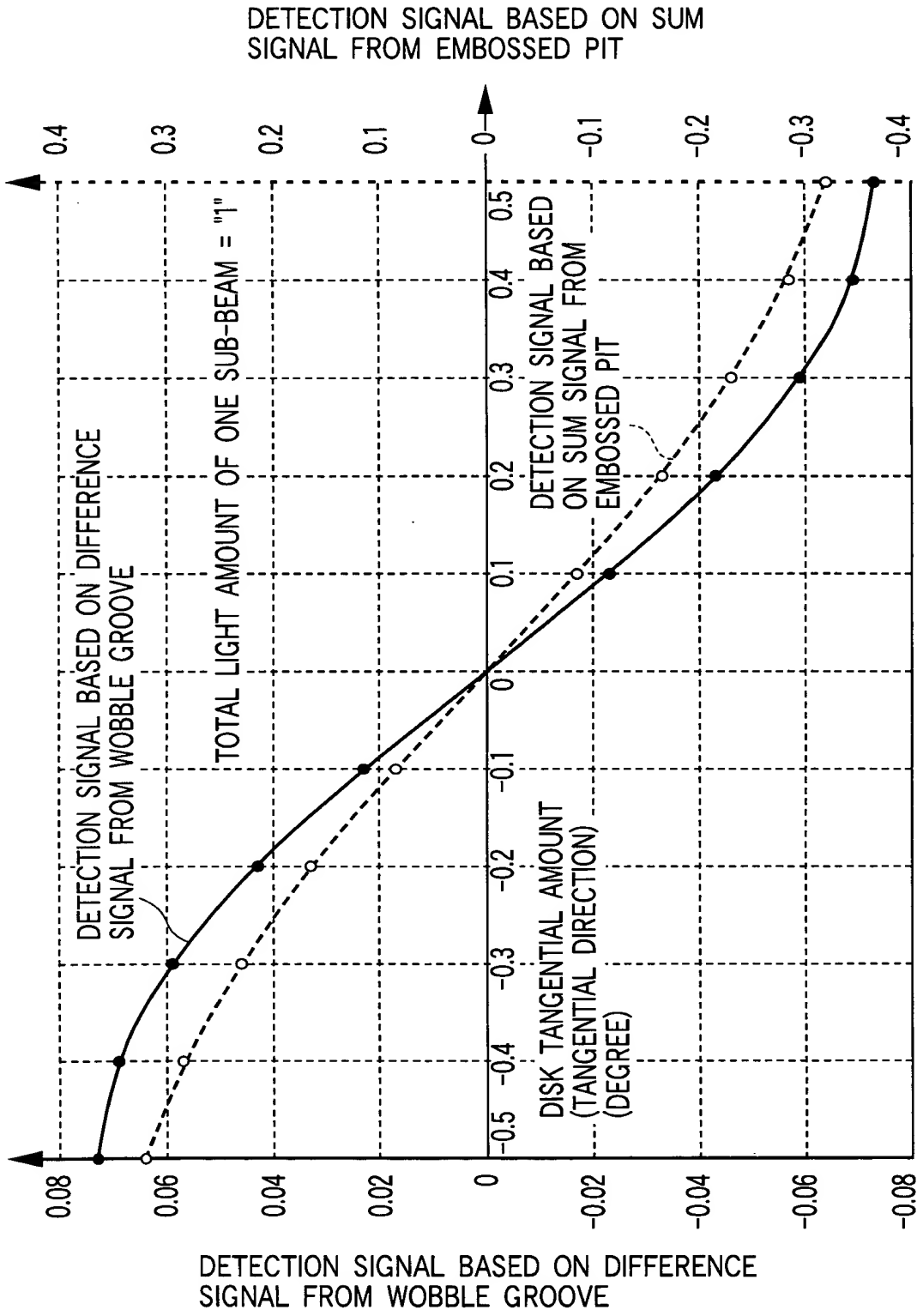
DETECTION SIGNAL BASED ON SUM SIGNAL FROM EMBOSSED PIT
0.4
0.3
0.2
0.1
0
-0.1
-0.2
-0.3
-0.4
DETECTION SIGNAL BASED ON DIFFERENCE SIGNAL FROM WOBBLE GROOVE
TOTAL LIGHT AMOUNT OF ONE SUB-BEAM = "1"
DETECTION SIGNAL BASED ON SUM SIGNAL FROM EMBOSSED PIT
0.5
0.4
0.3
0.2
0.1
0
-0.1
-0.2
-0.3
-0.4
-0.5
DISK TANGENTIAL AMOUNT (TANGENTIAL DIRECTION) (DEGREE)
0.08
0.06
0.04
0.02
0
-0.02
-0.04
-0.06
-0.08
DETECTION SIGNAL BASED ON DIFFERENCE SIGNAL FROM WOBBLE GROOVE

FIG. 18

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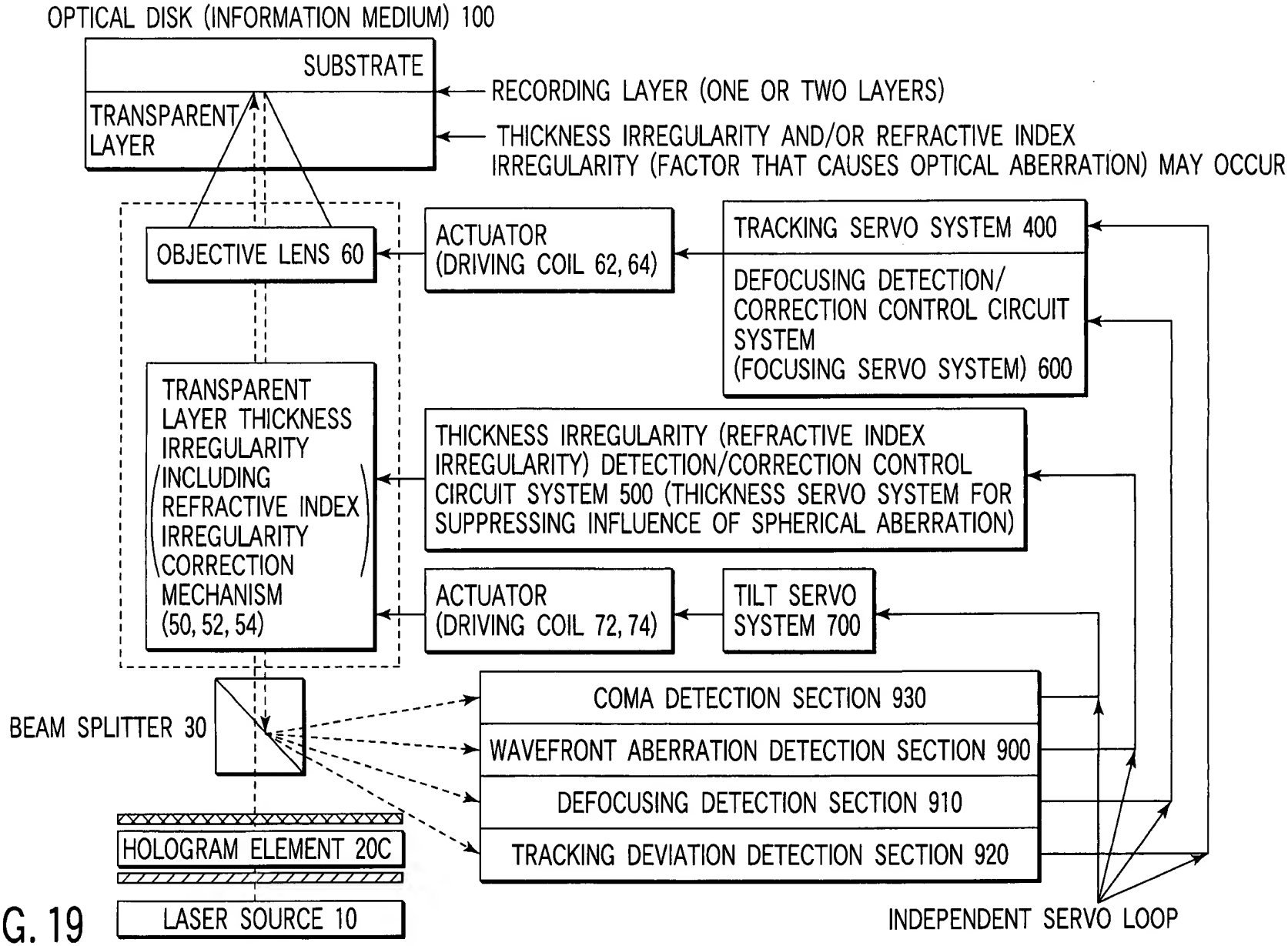

FIG. 19

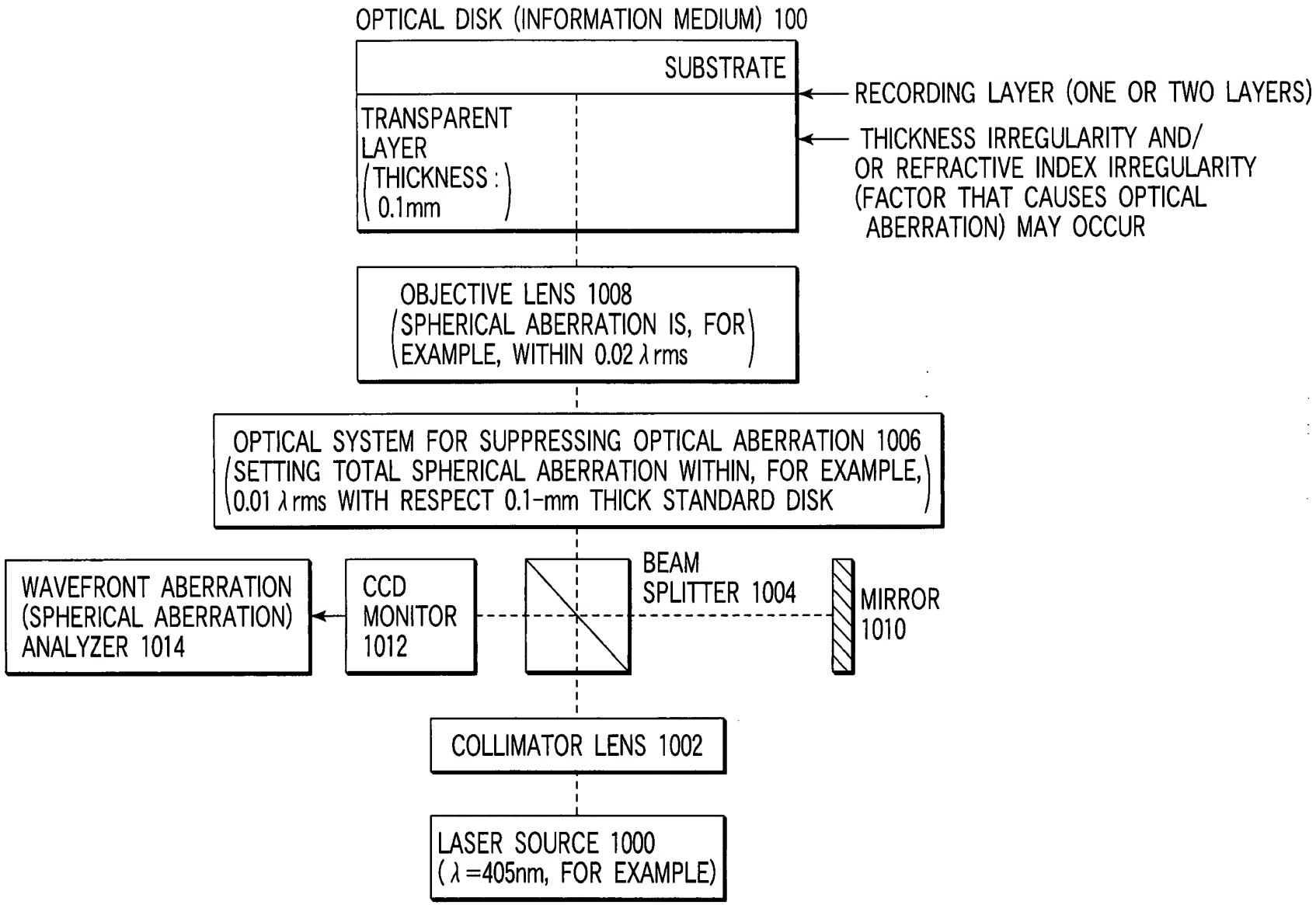

FIG. 20

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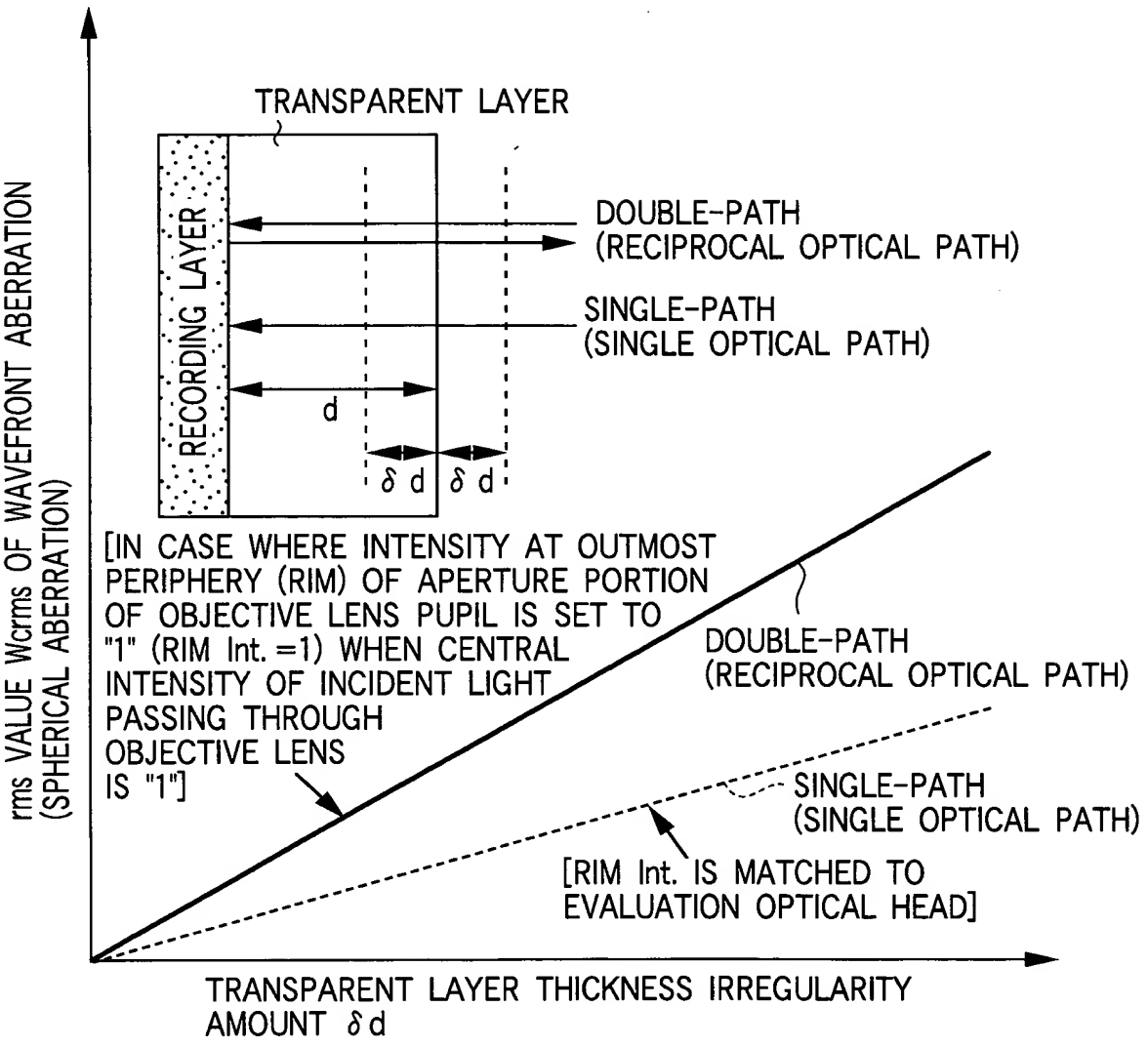
TRANSPARENT LAYER
RECORDING LAYER
DOUBLE-PATH
(RECIPROCAL OPTICAL PATH)
SINGLE-PATH
(SINGLE OPTICAL PATH)
d
δ d
δ d
[IN CASE WHERE INTENSITY AT OUTMOST PERIPHERY (RIM) OF APERTURE PORTION OF OBJECTIVE LENS PUPIL IS SET TO "1" (RIM Int. =1) WHEN CENTRAL INTENSITY OF INCIDENT LIGHT PASSING THROUGH OBJECTIVE LENS IS "1"]
DOUBLE-PATH
(RECIPROCAL OPTICAL PATH)
SINGLE-PATH
(SINGLE OPTICAL PATH)
[RIM Int. IS MATCHED TO EVALUATION OPTICAL HEAD]
rms VALUE Wcrms OF WAVEFRONT ABERRATION
(SPHERICAL ABERRATION)
TRANSPARENT LAYER THICKNESS IRREGULARITY AMOUNT δ d

FIG. 21

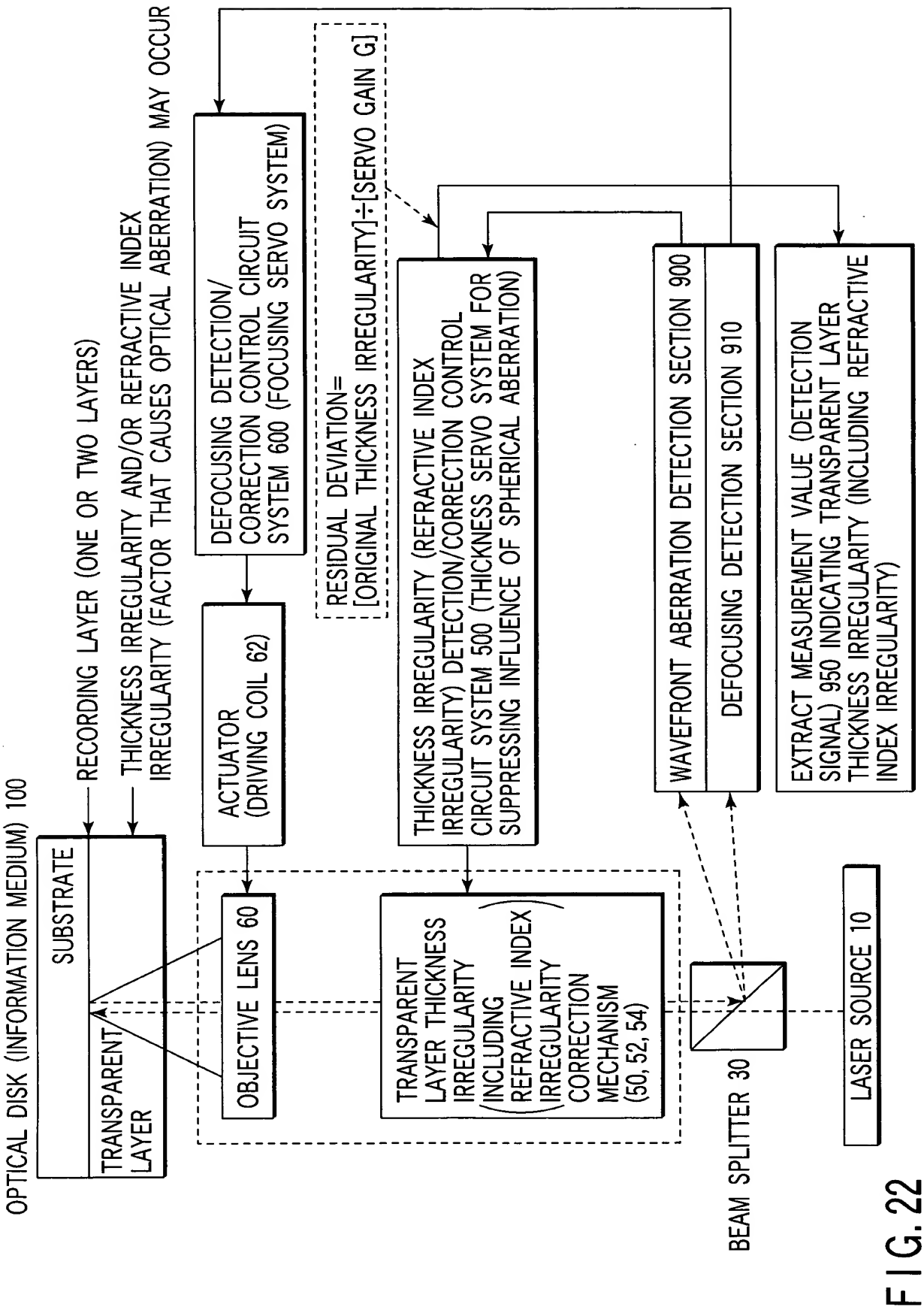
OPTICAL DISK (INFORMATION MEDIUM) 100
SUBSTRATE
TRANSPARENT LAYER
RECORDING LAYER (ONE OR TWO LAYERS)
THICKNESS IRREGULARITY AND/OR REFRACTIVE INDEX IRREGULARITY (FACTOR THAT CAUSES OPTICAL ABERRATION) MAY OCCUR
OBJECTIVE LENS 60
ACTUATOR (DRIVING COIL 62)
DEFOCUSING DETECTION/ CORRECTION CONTROL CIRCUIT SYSTEM 600 (FOCUSING SERVO SYSTEM)
RESIDUAL DEVIATION= [ORIGINAL THICKNESS IRREGULARITY]÷[SERVO GAIN G]
THICKNESS IRREGULARITY (REFRACTIVE INDEX IRREGULARITY) DETECTION/CORRECTION CONTROL CIRCUIT SYSTEM 500 (THICKNESS SERVO SYSTEM FOR SUPPRESSING INFLUENCE OF SPHERICAL ABERRATION)
TRANSPARENT LAYER THICKNESS IRREGULARITY (INCLUDING REFRACTIVE INDEX IRREGULARITY) CORRECTION MECHANISM (50, 52, 54)
WAVEFRONT ABERRATION DETECTION SECTION 900
DEFOCUSING DETECTION SECTION 910
EXTRACT MEASUREMENT VALUE (DETECTION SIGNAL) 950 INDICATING TRANSPARENT LAYER THICKNESS IRREGULARITY (INCLUDING REFRACTIVE INDEX IRREGULARITY)
BEAM SPLITTER 30
LASER SOURCE 10

FIG. 22

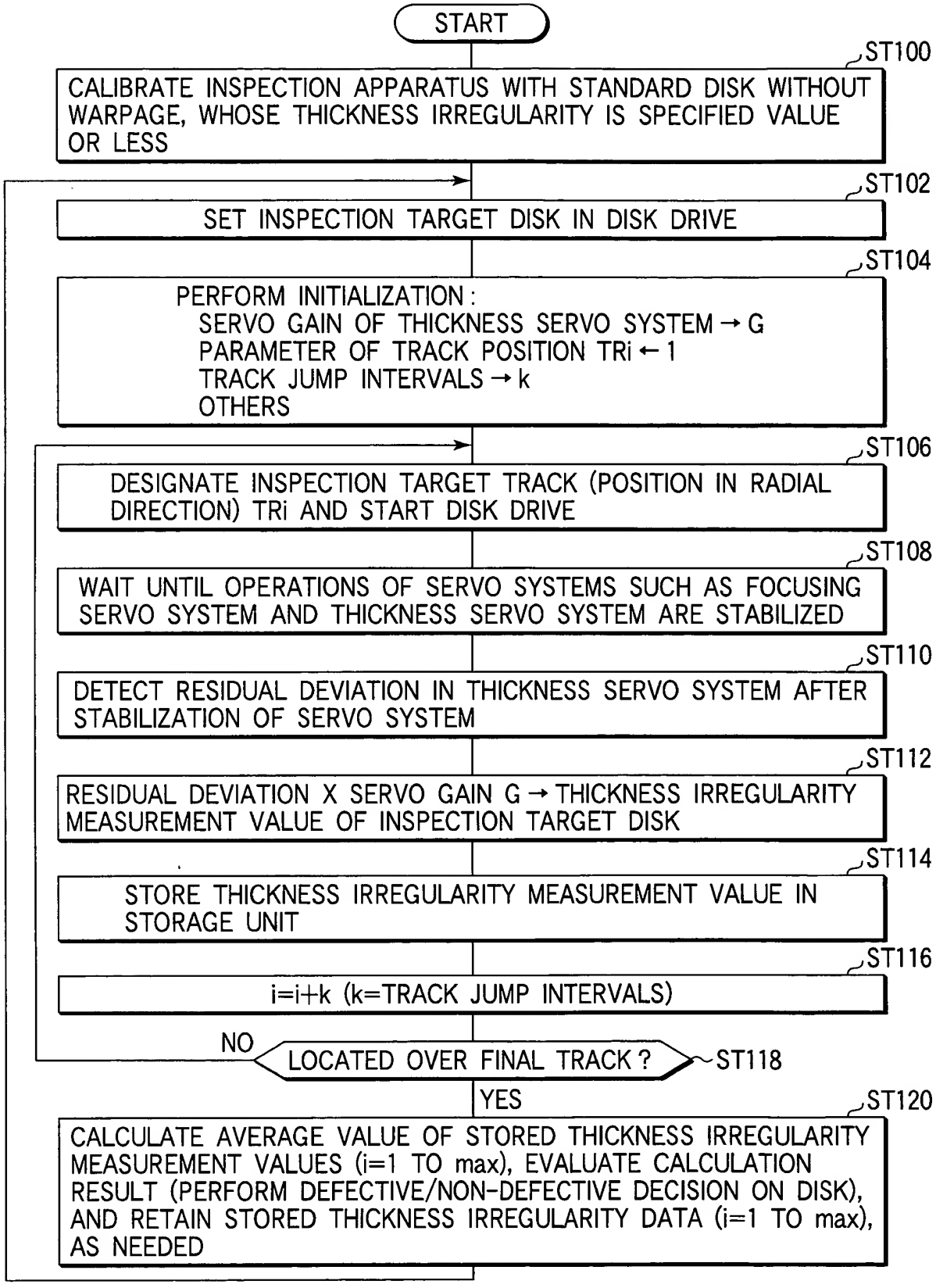
START
ST100
CALIBRATE INSPECTION APPARATUS WITH STANDARD DISK WITHOUT WARPAGE, WHOSE THICKNESS IRREGULARITY IS SPECIFIED VALUE OR LESS
ST102
SET INSPECTION TARGET DISK IN DISK DRIVE
ST104
PERFORM INITIALIZATION:
SERVO GAIN OF THICKNESS SERVO SYSTEM → G
PARAMETER OF TRACK POSITION TRi ← 1
TRACK JUMP INTERVALS → k
OTHERS
ST106
DESIGNATE INSPECTION TARGET TRACK (POSITION IN RADIAL DIRECTION) TRi AND START DISK DRIVE
ST108
WAIT UNTIL OPERATIONS OF SERVO SYSTEMS SUCH AS FOCUSING SERVO SYSTEM AND THICKNESS SERVO SYSTEM ARE STABILIZED
ST110
DETECT RESIDUAL DEVIATION IN THICKNESS SERVO SYSTEM AFTER STABILIZATION OF SERVO SYSTEM
ST112
RESIDUAL DEVIATION X SERVO GAIN G → THICKNESS IRREGULARITY MEASUREMENT VALUE OF INSPECTION TARGET DISK
ST114
STORE THICKNESS IRREGULARITY MEASUREMENT VALUE IN STORAGE UNIT
ST116
i=i+k (k=TRACK JUMP INTERVALS)
NO
LOCATED OVER FINAL TRACK?
ST118
YES
ST120
CALCULATE AVERAGE VALUE OF STORED THICKNESS IRREGULARITY MEASUREMENT VALUES (i=1 TO max), EVALUATE CALCULATION RESULT (PERFORM DEFECTIVE/NON-DEFECTIVE DECISION ON DISK), AND RETAIN STORED THICKNESS IRREGULARITY DATA (i=1 TO max), AS NEEDED

FIG. 23

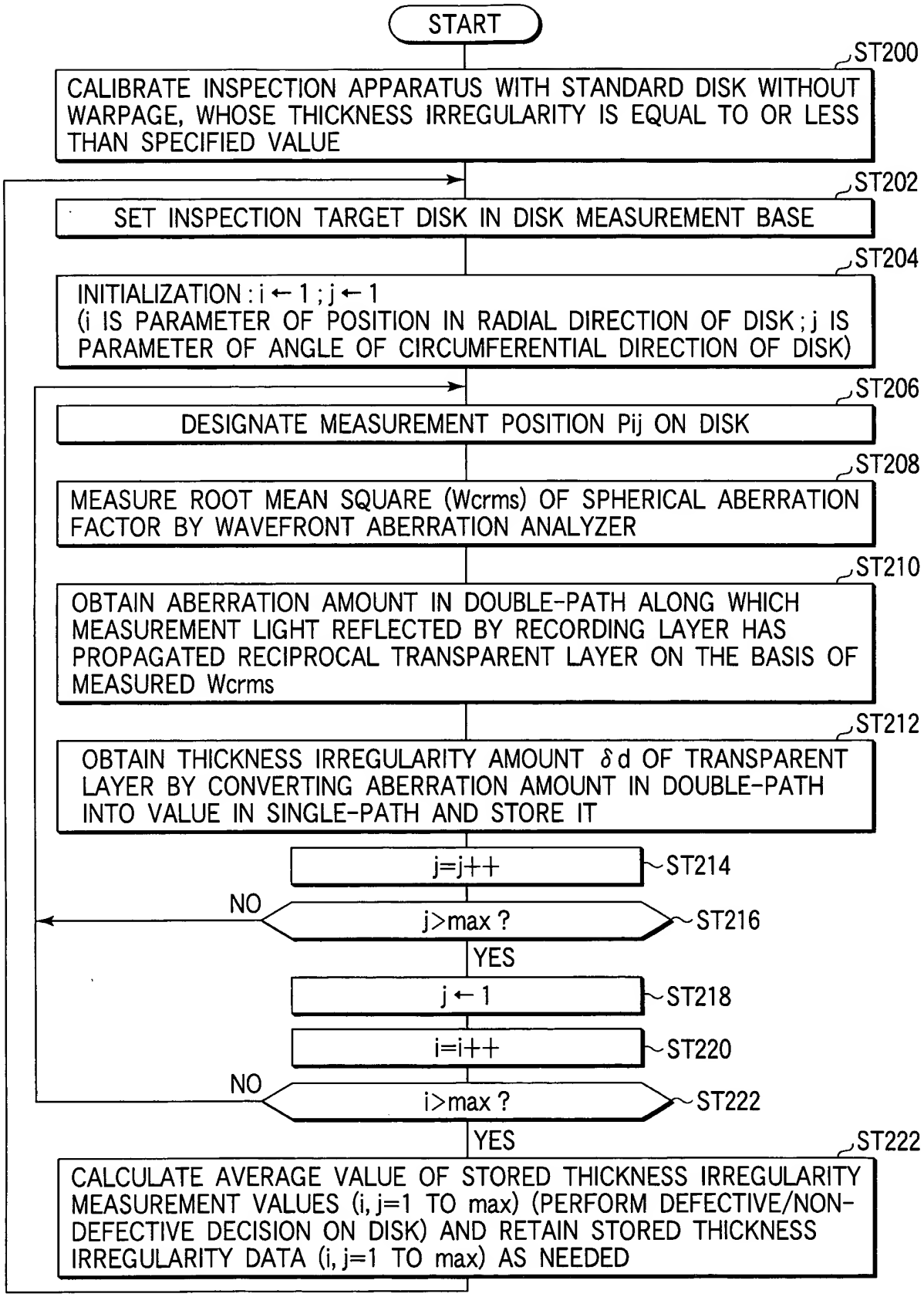
START
ST200
CALIBRATE INSPECTION APPARATUS WITH STANDARD DISK WITHOUT WARPAGE, WHOSE THICKNESS IRREGULARITY IS EQUAL TO OR LESS THAN SPECIFIED VALUE
ST202
SET INSPECTION TARGET DISK IN DISK MEASUREMENT BASE
ST204
INITIALIZATION : i ← 1 ; j ← 1
(i IS PARAMETER OF POSITION IN RADIAL DIRECTION OF DISK ; j IS PARAMETER OF ANGLE OF CIRCUMFERENTIAL DIRECTION OF DISK)
ST206
DESIGNATE MEASUREMENT POSITION Pij ON DISK
ST208
MEASURE ROOT MEAN SQUARE (Wcrms) OF SPHERICAL ABERRATION FACTOR BY WAVEFRONT ABERRATION ANALYZER
ST210
OBTAIN ABERRATION AMOUNT IN DOUBLE-PATH ALONG WHICH MEASUREMENT LIGHT REFLECTED BY RECORDING LAYER HAS PROPAGATED RECIPROCAL TRANSPARENT LAYER ON THE BASIS OF MEASURED Wcrms
ST212
OBTAIN THICKNESS IRREGULARITY AMOUNT δd OF TRANSPARENT LAYER BY CONVERTING ABERRATION AMOUNT IN DOUBLE-PATH INTO VALUE IN SINGLE-PATH AND STORE IT
j=j++
ST214
NO
j>max ?
ST216
YES
j ← 1
ST218
i=i++
ST220
NO
i>max ?
ST222
YES
ST222
CALCULATE AVERAGE VALUE OF STORED THICKNESS IRREGULARITY MEASUREMENT VALUES (i, j=1 TO max) (PERFORM DEFECTIVE/NON-DEFECTIVE DECISION ON DISK) AND RETAIN STORED THICKNESS IRREGULARITY DATA (i, j=1 TO max) AS NEEDED

FIG. 24

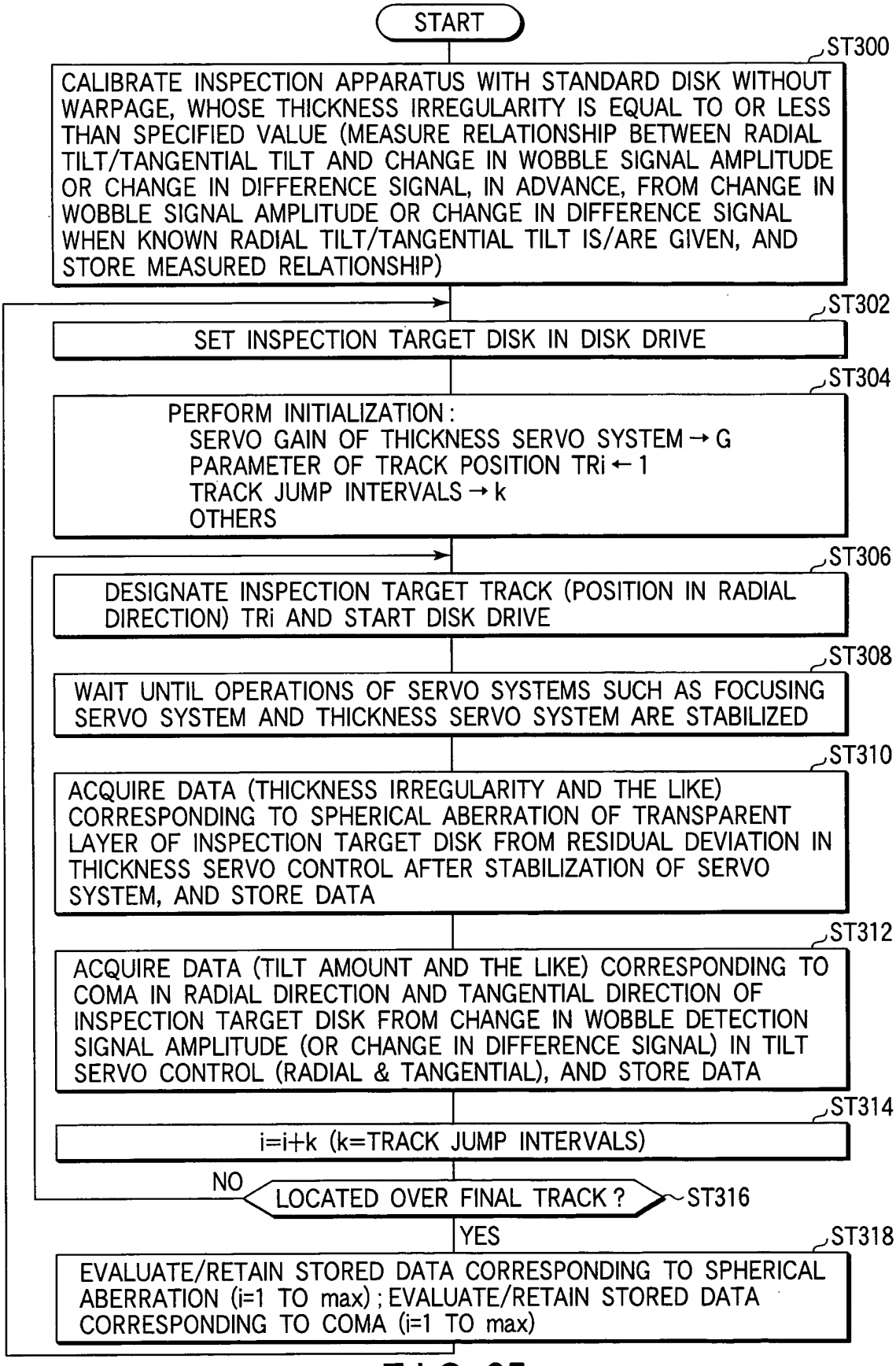
START
ST300
CALIBRATE INSPECTION APPARATUS WITH STANDARD DISK WITHOUT WARPAGE, WHOSE THICKNESS IRREGULARITY IS EQUAL TO OR LESS THAN SPECIFIED VALUE (MEASURE RELATIONSHIP BETWEEN RADIAL TILT/TANGENTIAL TILT AND CHANGE IN WOBBLE SIGNAL AMPLITUDE OR CHANGE IN DIFFERENCE SIGNAL, IN ADVANCE, FROM CHANGE IN WOBBLE SIGNAL AMPLITUDE OR CHANGE IN DIFFERENCE SIGNAL WHEN KNOWN RADIAL TILT/TANGENTIAL TILT IS/ARE GIVEN, AND STORE MEASURED RELATIONSHIP)
ST302
SET INSPECTION TARGET DISK IN DISK DRIVE
ST304
PERFORM INITIALIZATION:
SERVO GAIN OF THICKNESS SERVO SYSTEM → G
PARAMETER OF TRACK POSITION TRi ← 1
TRACK JUMP INTERVALS → k
OTHERS
ST306
DESIGNATE INSPECTION TARGET TRACK (POSITION IN RADIAL DIRECTION) TRi AND START DISK DRIVE
ST308
WAIT UNTIL OPERATIONS OF SERVO SYSTEMS SUCH AS FOCUSING SERVO SYSTEM AND THICKNESS SERVO SYSTEM ARE STABILIZED
ST310
ACQUIRE DATA (THICKNESS IRREGULARITY AND THE LIKE) CORRESPONDING TO SPHERICAL ABERRATION OF TRANSPARENT LAYER OF INSPECTION TARGET DISK FROM RESIDUAL DEVIATION IN THICKNESS SERVO CONTROL AFTER STABILIZATION OF SERVO SYSTEM, AND STORE DATA
ST312
ACQUIRE DATA (TILT AMOUNT AND THE LIKE) CORRESPONDING TO COMA IN RADIAL DIRECTION AND TANGENTIAL DIRECTION OF INSPECTION TARGET DISK FROM CHANGE IN WOBBLE DETECTION SIGNAL AMPLITUDE (OR CHANGE IN DIFFERENCE SIGNAL) IN TILT SERVO CONTROL (RADIAL & TANGENTIAL), AND STORE DATA
ST314
i=i+k (k=TRACK JUMP INTERVALS)
NO
LOCATED OVER FINAL TRACK?
ST316
YES
ST318
EVALUATE/RETAIN STORED DATA CORRESPONDING TO SPHERICAL ABERRATION (i=1 TO max); EVALUATE/RETAIN STORED DATA CORRESPONDING TO COMA (i=1 TO max)

FIG. 25

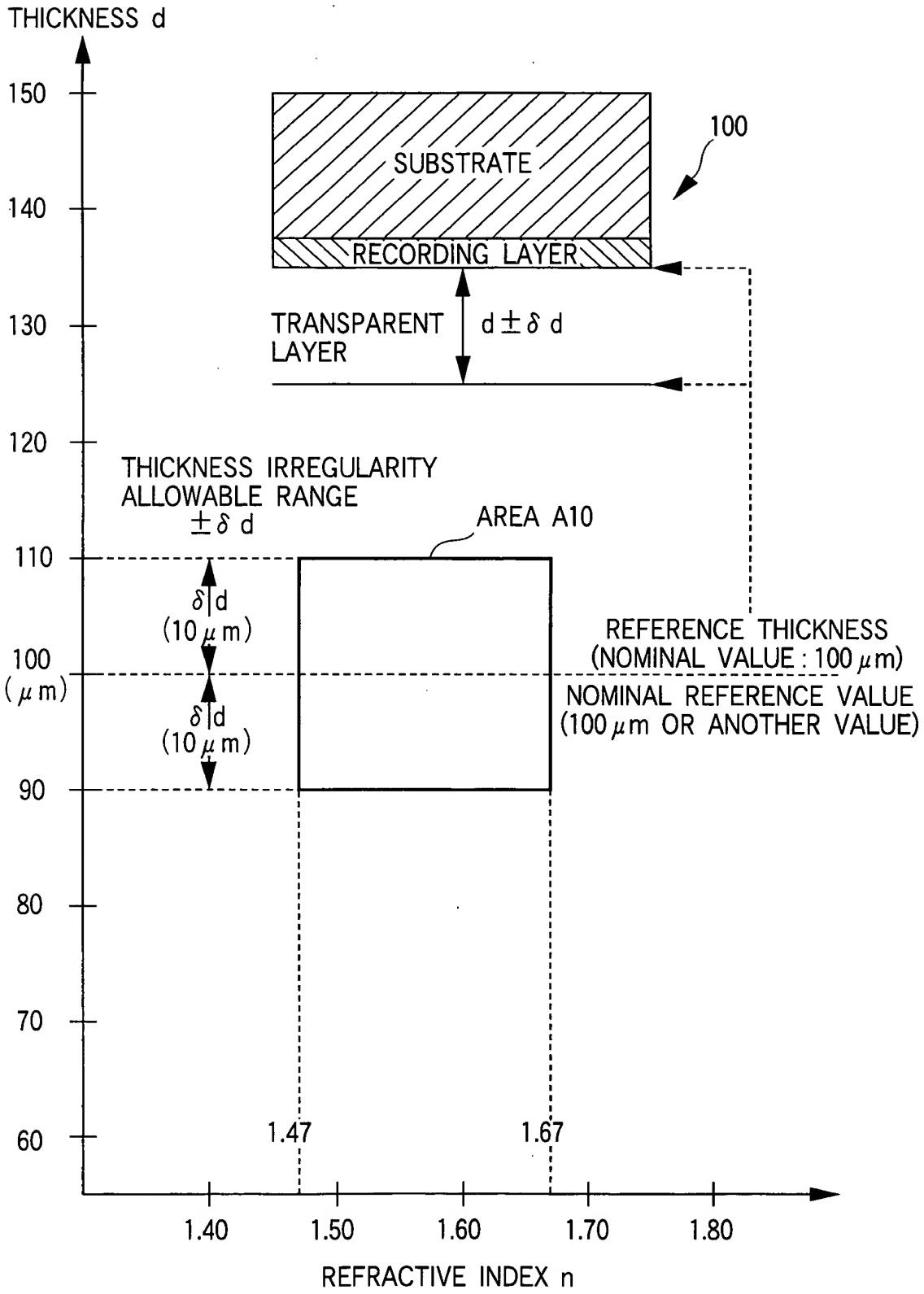
THICKNESS d
150
140
130
120
110
100
(μm)
90
80
70
60
SUBSTRATE
100
RECORDING LAYER
TRANSPARENT LAYER
d ± δ d
THICKNESS IRREGULARITY ALLOWABLE RANGE ± δ d
AREA A10
δ d (10 μm)
δ d (10 μm)
REFERENCE THICKNESS (NOMINAL VALUE : 100 μm)
NOMINAL REFERENCE VALUE (100 μm OR ANOTHER VALUE)
1.47
1.67
1.40
1.50
1.60
1.70
1.80
REFRACTIVE INDEX n

FIG. 26

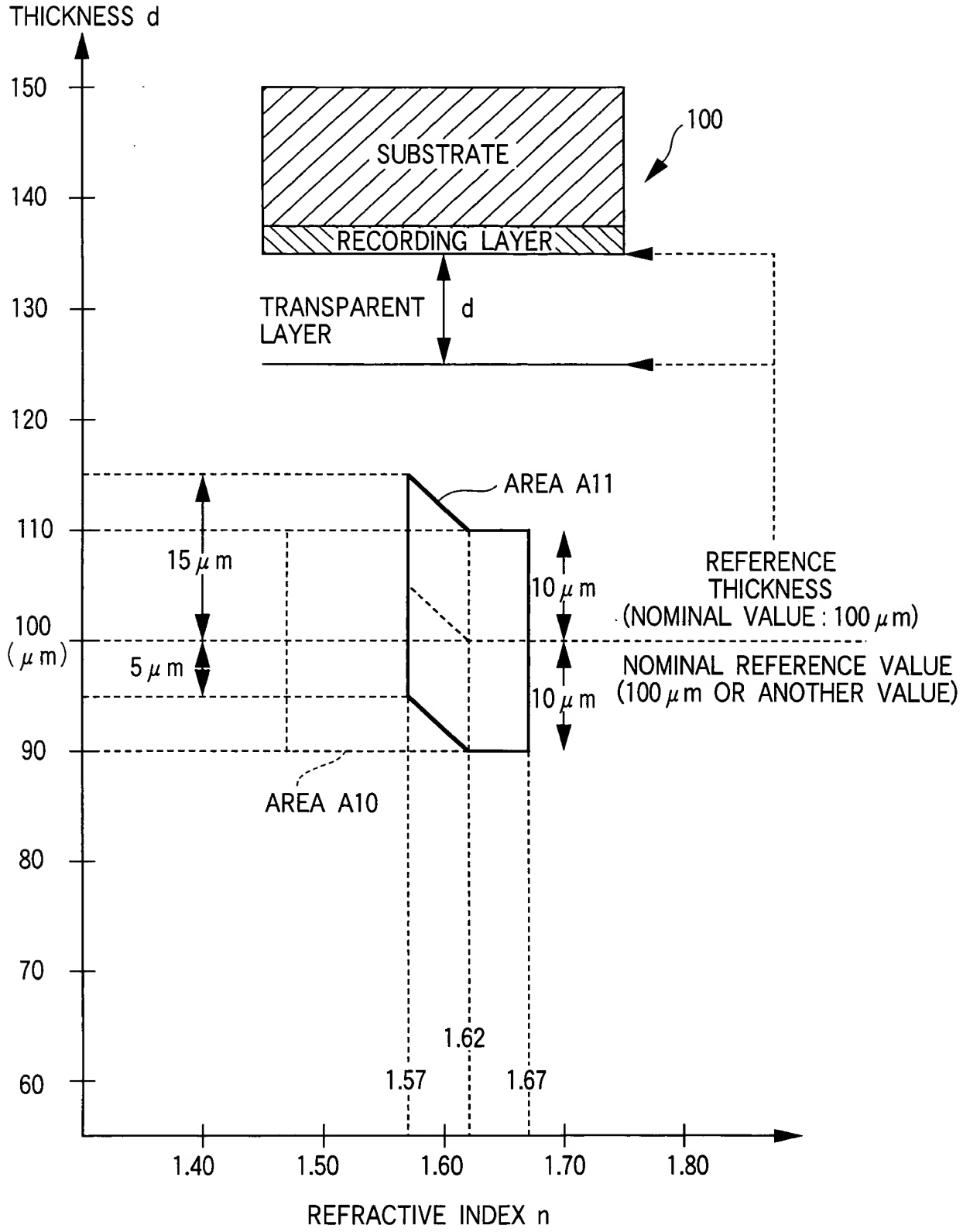
THICKNESS d
150
140
130
120
110
100
(μm)
90
80
70
60
SUBSTRATE
100
RECORDING LAYER
TRANSPARENT LAYER
d
AREA A11
15μm
10μm
REFERENCE THICKNESS
(NOMINAL VALUE : 100μm)
5μm
NOMINAL REFERENCE VALUE
(100μm OR ANOTHER VALUE)
10μm
AREA A10
1.62
1.57
1.67
1.40
1.50
1.60
1.70
1.80
REFRACTIVE INDEX n

FIG. 27

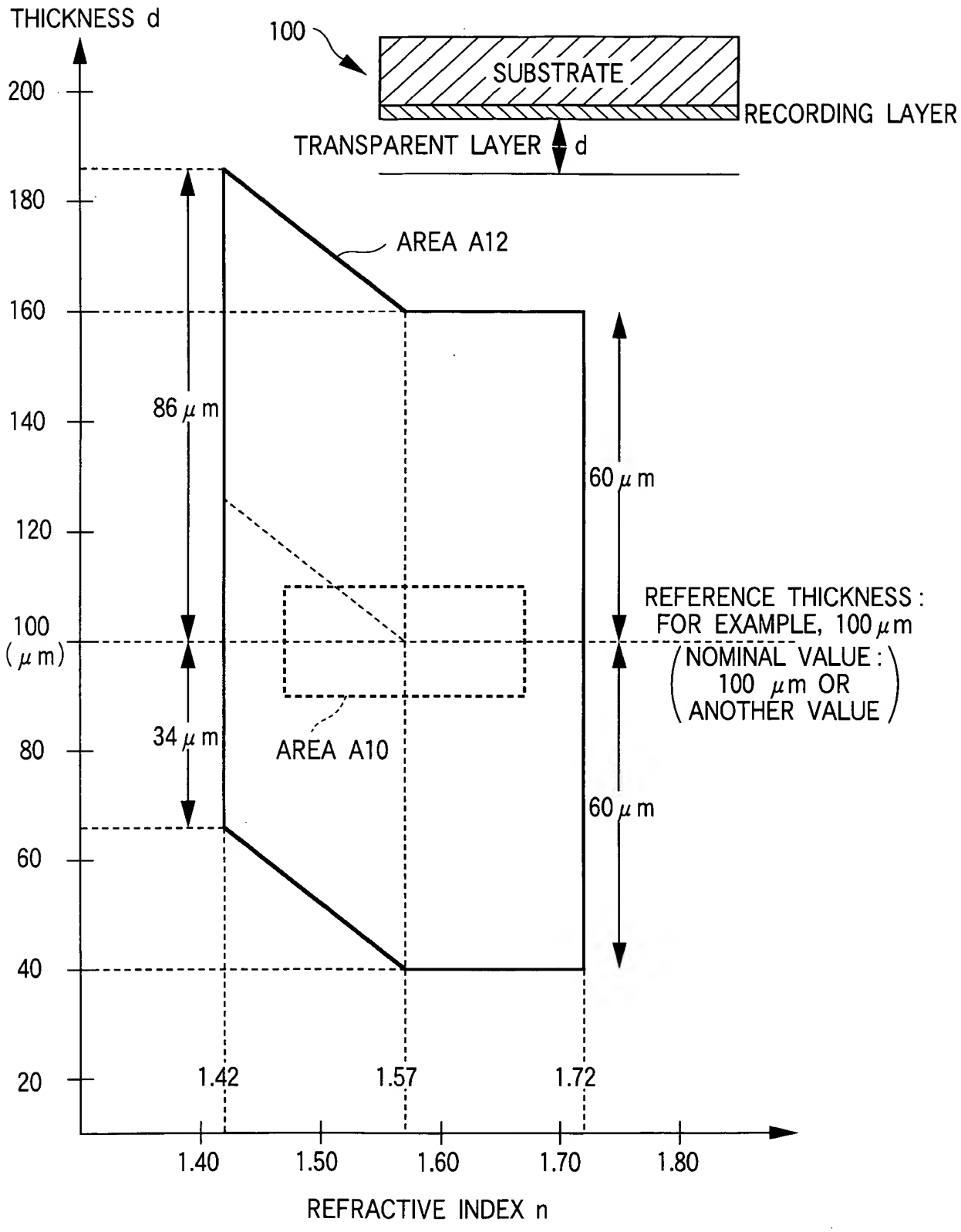
THICKNESS d
100
SUBSTRATE
RECORDING LAYER
TRANSPARENT LAYER
d
200
180
160
140
120
100
(μm)
80
60
40
20
AREA A12
86 μm
60 μm
REFERENCE THICKNESS :
FOR EXAMPLE, 100 μm
(NOMINAL VALUE :
100 μm OR
ANOTHER VALUE)
34 μm
AREA A10
60 μm
1.42
1.57
1.72
1.40
1.50
1.60
1.70
1.80
REFRACTIVE INDEX n

FIG. 28

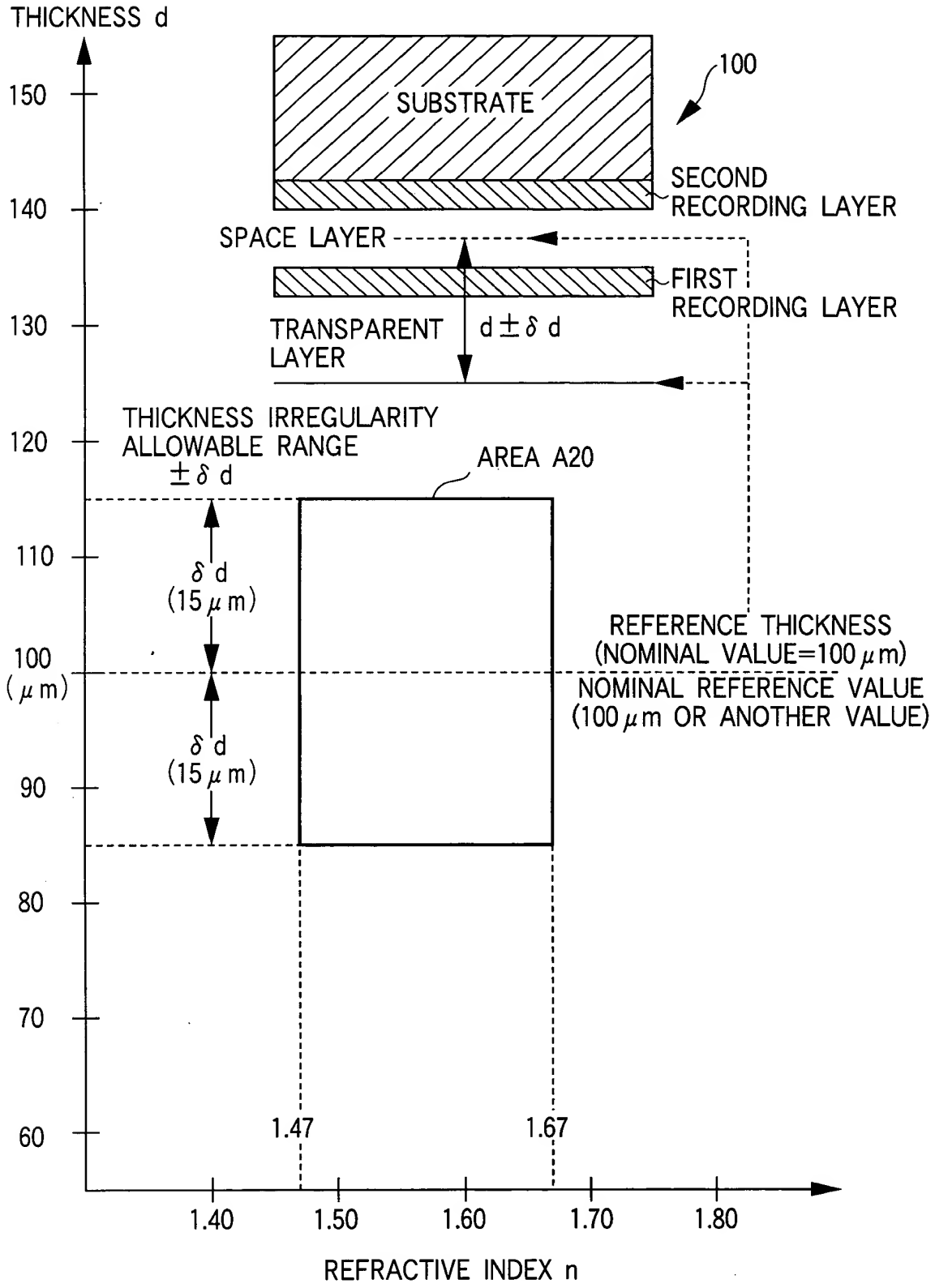
THICKNESS d
150
140
130
120
110
100
(μm)
90
80
70
60
SUBSTRATE
100
SECOND
RECORDING LAYER
SPACE LAYER
FIRST
RECORDING LAYER
TRANSPARENT
LAYER
d±δd
THICKNESS IRREGULARITY
ALLOWABLE RANGE
±δd
AREA A20
δd
(15μm)
δd
(15μm)
REFERENCE THICKNESS
(NOMINAL VALUE=100μm)
NOMINAL REFERENCE VALUE
(100μm OR ANOTHER VALUE)
1.47
1.67
1.40
1.50
1.60
1.70
1.80
REFRACTIVE INDEX n

FIG. 29

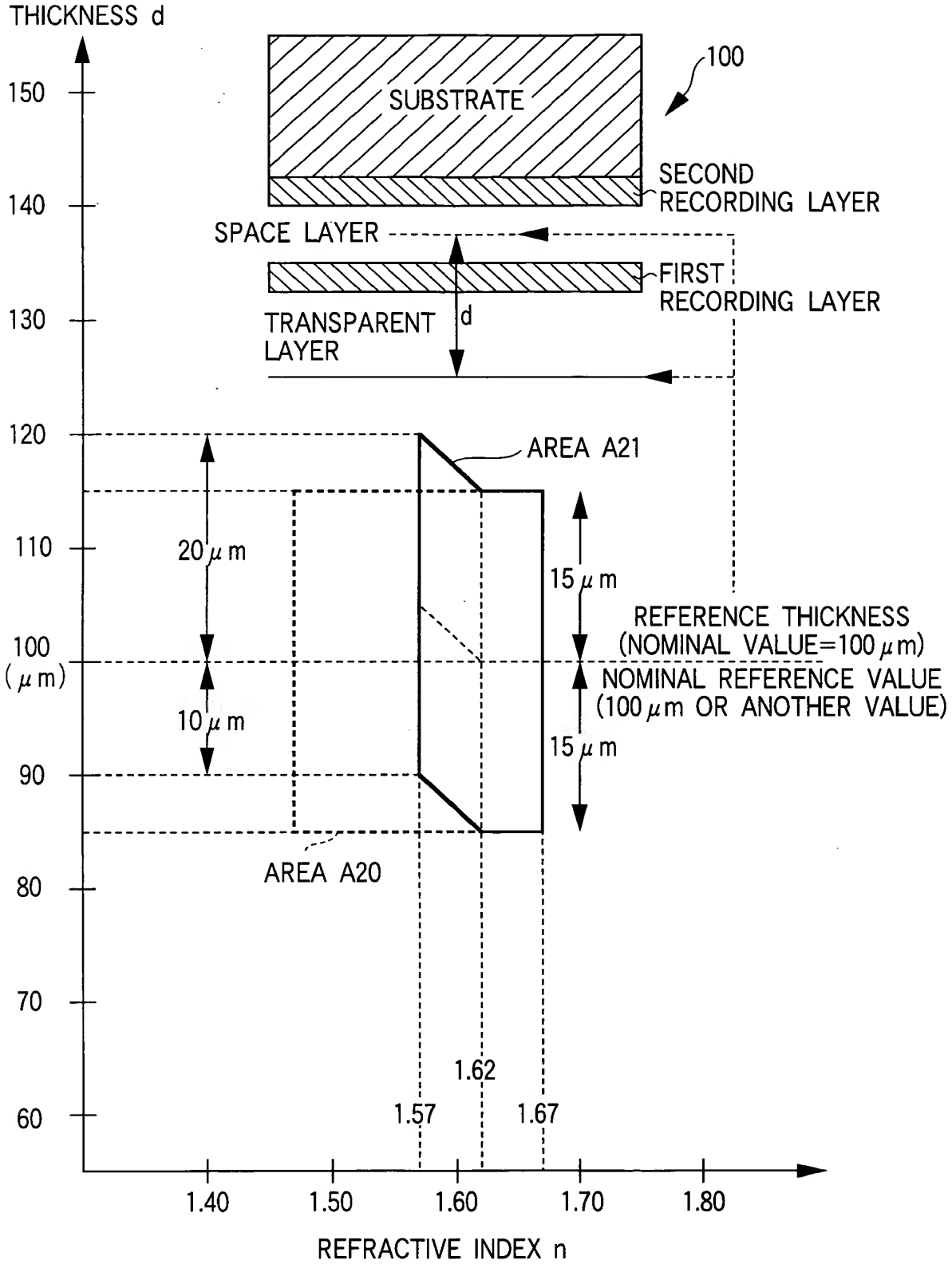
THICKNESS d
150
140
130
120
110
100
(μm)
90
80
70
60
SUBSTRATE
100
SECOND
RECORDING LAYER
SPACE LAYER
FIRST
RECORDING LAYER
TRANSPARENT
LAYER
d
AREA A21
20μm
10μm
15μm
REFERENCE THICKNESS
(NOMINAL VALUE=100μm)
NOMINAL REFERENCE VALUE
(100μm OR ANOTHER VALUE)
15μm
AREA A20
1.62
1.57
1.67
1.40
1.50
1.60
1.70
1.80
REFRACTIVE INDEX n

FIG. 30

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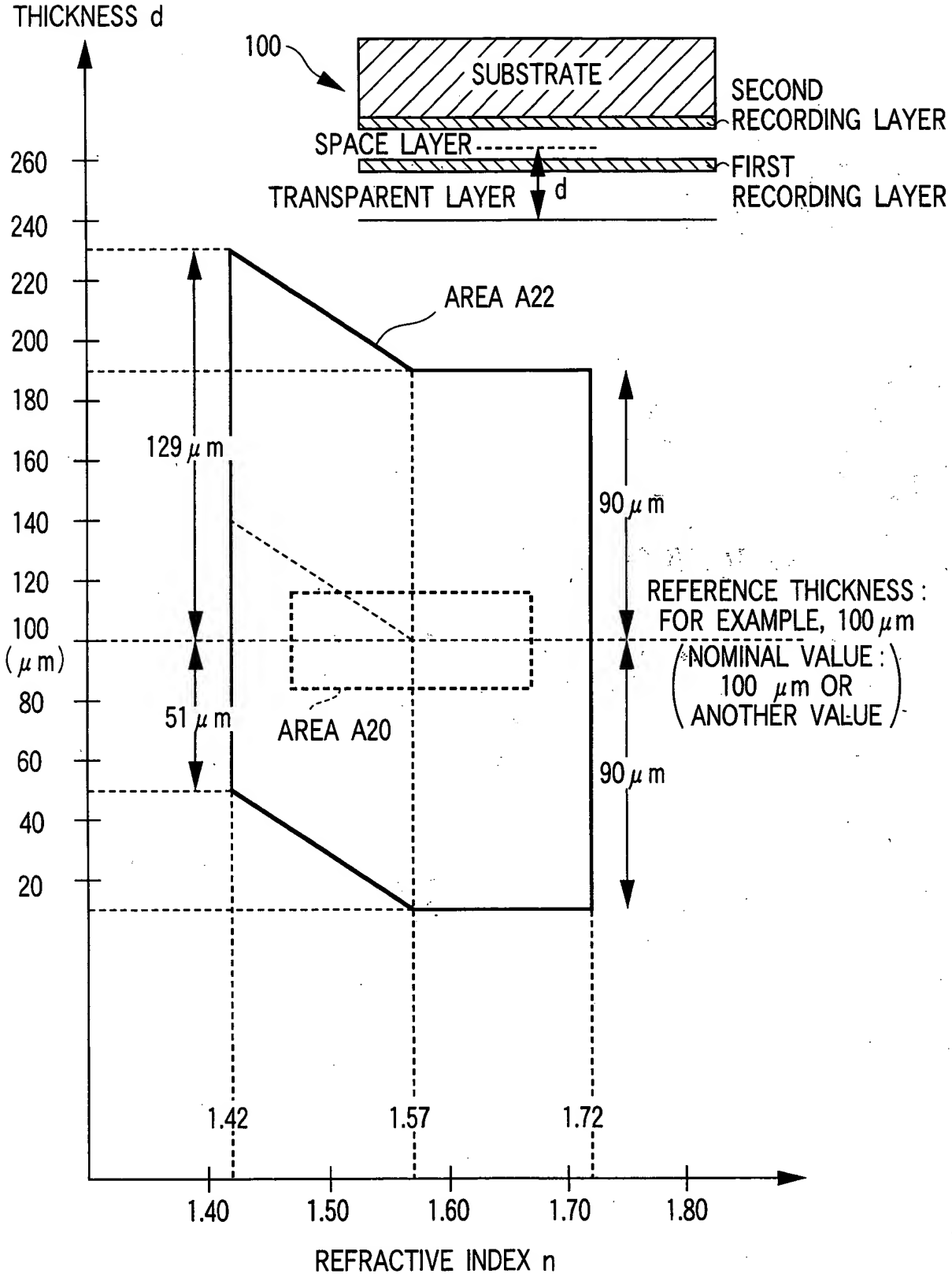

FIG. 31